

Core-to-Core Program



A study on various gain calibration methods of the photo-sensor, SiPM

光検出器SiPMのゲイン較正手法に関する研究

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Outline

- Introduction: About SiPM
- Statistical Method
- Waveform Method

SiPM

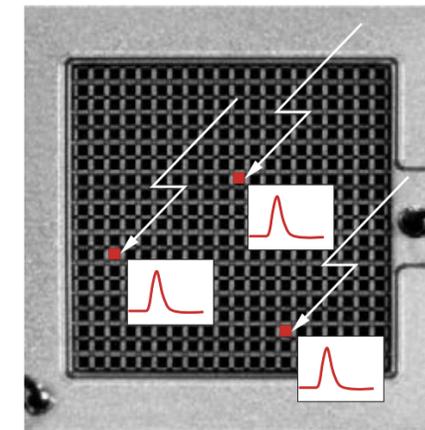
- SiPM is photon detector made of semiconductor.
 - Photon generates electron & hole pair.
 - multiplication of electron by avalanche
 - same output from a cell (Geiger mode) → photoncounting

○ Advantage

- small
- low bias voltage
- can be used in B field

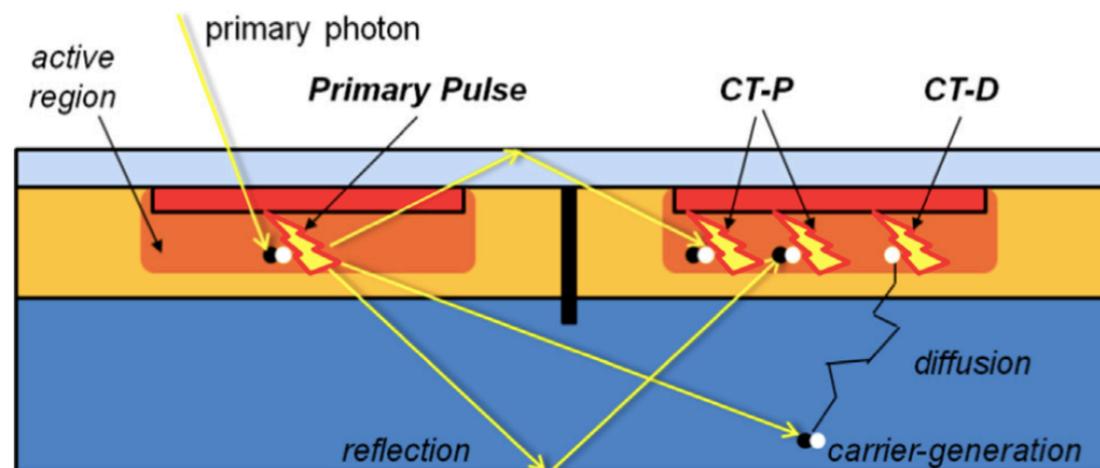
○ Noise

- Dark Count
- Crosstalk
- Afterpulsing



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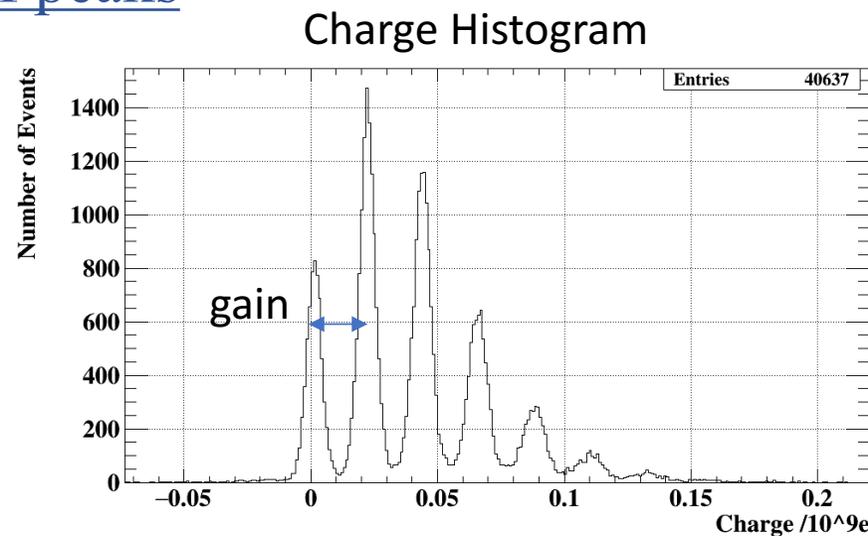
Hamamatsu 光半導体素子ハンドブック



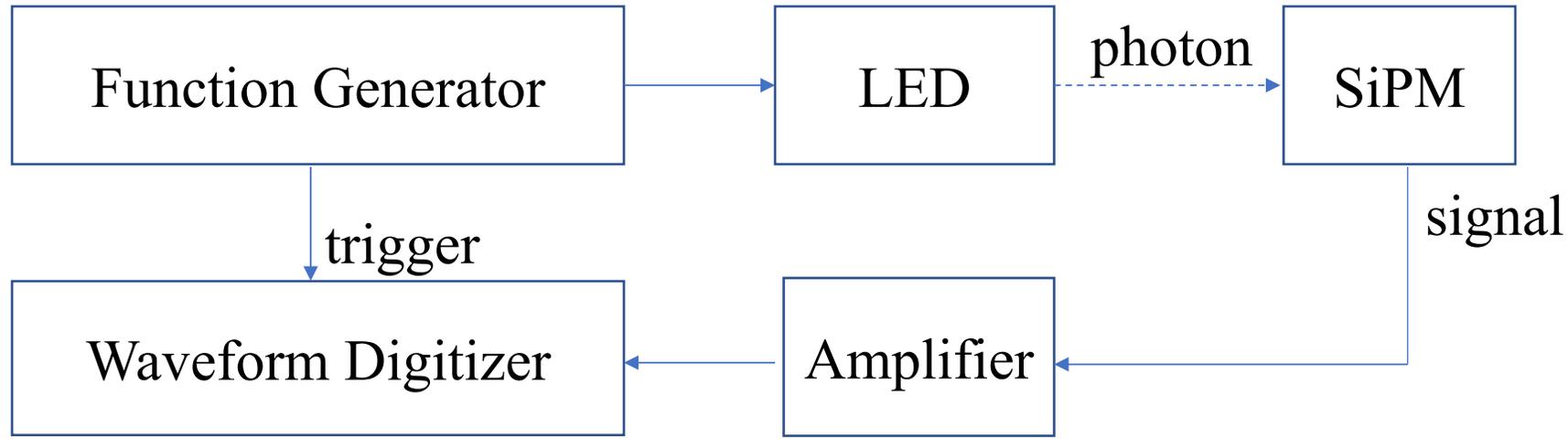
Ferenc Nagy et al. "Afterpulse and delayed crosstalk analysis on a STMicroelectronics silicon photomultiplier", Nuclear Instruments and Methods in Physics Research A 759 (2014) 44 – 49

Gain

- Gain: relation b/w output & # of photoelectrons
 - depends on over voltage, temperature, ...
 - must be checked regularly in experiment
- Measuring Gain from single p.e. (photoelectron)
 - Since SiPM can detect 1 photon, output charge distribution has peak structure.
 - Gain can be directly obtained from interval of peaks
 - Limitation
 - need good S/N to separate each peak
 - need dedicated run if dark count rate is small
 - We will introduce redundant methods



Set up



- SiPM : MPPC S13360-3050PE (Hamamatsu)
 - effective area : 3 mm × 3 mm
 - pixel pitch : 50 μm
 - # of pixels : 3600
- Amplifier : MAR amplifier (PSI) (amplification factor: ~70)
- Waveform Digitizer : DRS4 chip (PSI)
 - sampling rate : 1.6 GHz
- Temperature was kept at 23 °C

Outline

- Introduction: About SiPM
- Statistical Method
- Waveform Method

Previous Study: PMT

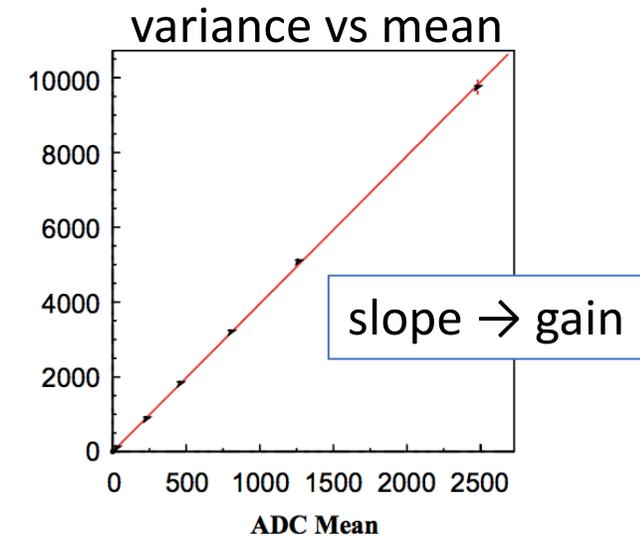
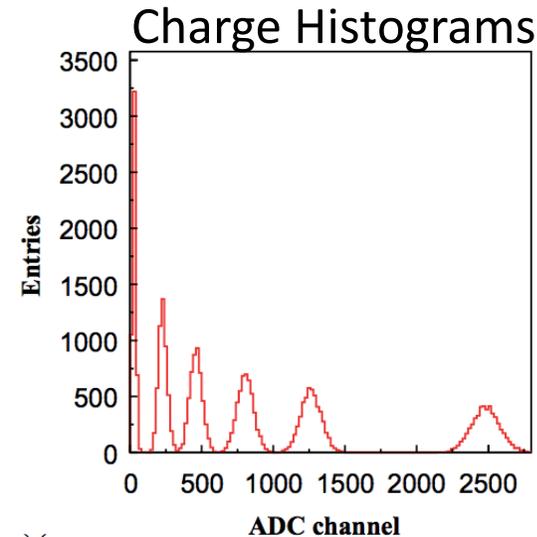
- When # of photoelectrons follows Poisson distribution (mean: μ), mean & variance of output charge are

- $mean = gain \cdot \mu$
- $variance = gain^2 \cdot \mu$



$$gain = \frac{variance}{mean}$$

- Charge distribution is broadened by Gaussian noise (σ).
 → subtract σ^2 from variance
- already used in experiments (ex. MEG)



Previous Study: SiPM

- Assuming # of crosstalks from 1 cell follows Poisson distribution, total # of p.e. follows Generalized Poisson distribution.

$$GP_{\mu,\lambda}(k) := \frac{\mu(\mu+k\lambda)^{k-1} e^{-(\mu+k\lambda)}}{k!}$$

μ : mean w/o crosstalk
 λ : crosstalk probability

- $E[k] = \frac{\mu}{1-\lambda}$
- $V[k] = \frac{\mu}{(1-\lambda)^3}$

✂ when each of crosstalk & after-pulse probability < 25 %

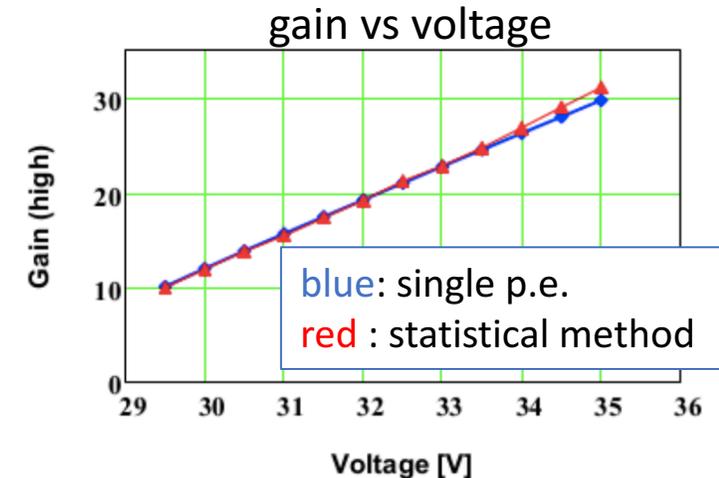
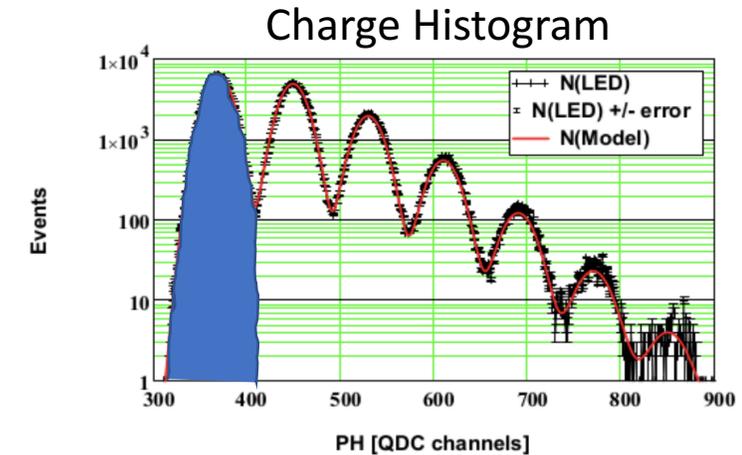
- Then, defining Excess Noise Factor as $ENF := \mu \frac{\text{variance}}{\text{mean}^2}$,

$$\text{gain} = \frac{1}{ENF^2} \frac{\text{variance}}{\text{mean}}$$

- ENF is calculated from pedestal fraction.

$$GP_{\mu,\lambda}(k=0) = e^{-\mu}$$

- tested with KETEK SiPM (4384 pixels, $15\mu\text{m} \times 15\mu\text{m}$ area)



Characteristics of the Method

➤ Advantage

- can be used even when peaks are not separated
 - when S/N is bad
 - when using strong light

➤ Limitation

- Constant light source is necessary.
- need to know or assume ENF beforehand

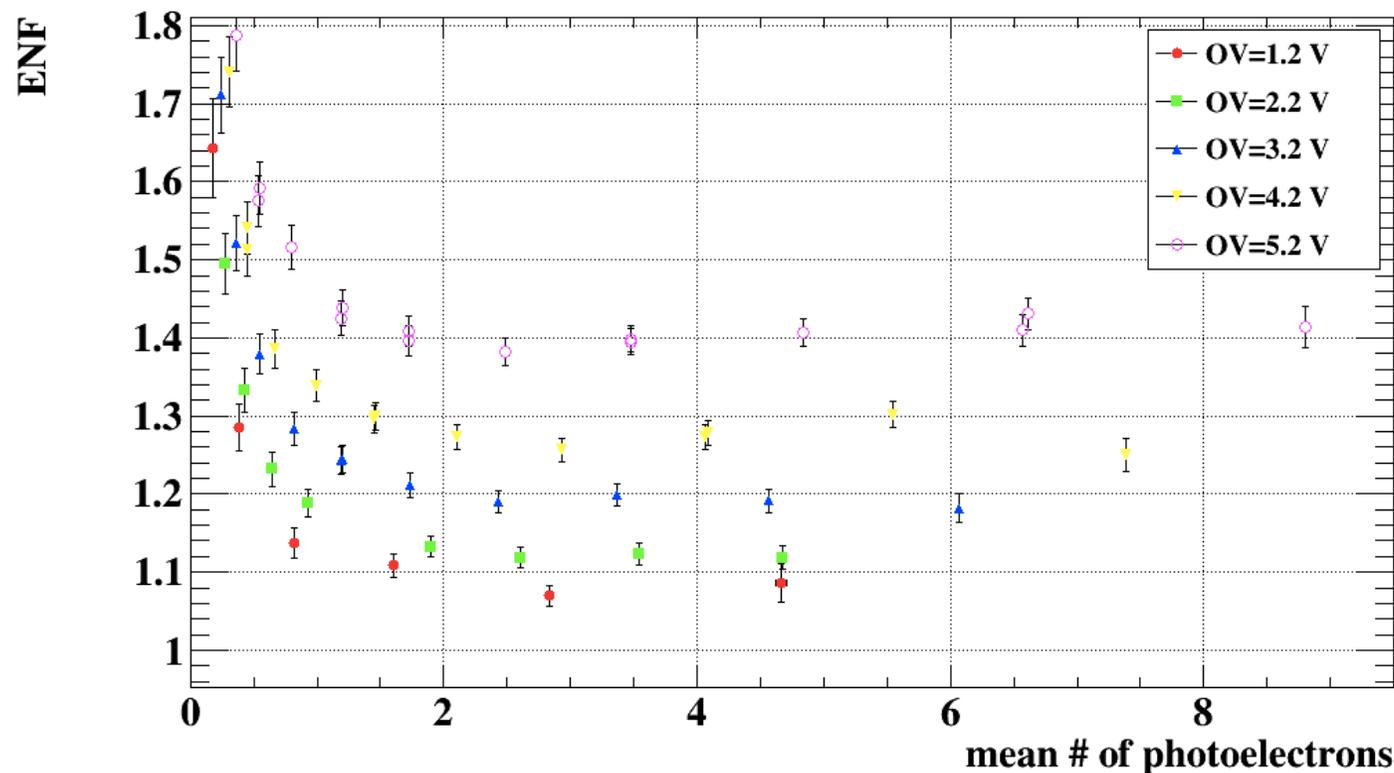
We tried this method with Hamamatsu MPPC.

→ Some problems were found.

- ENF depends on light intensity
- variance/mean depends on light intensity

ENF Variation

ENF vs Light Intensity



$$ENF := \mu \frac{\text{variance}}{\text{mean}^2}$$

$$\text{gain} = \frac{1}{ENF^2} \frac{\text{variance}}{\text{mean}}$$

Over Voltage

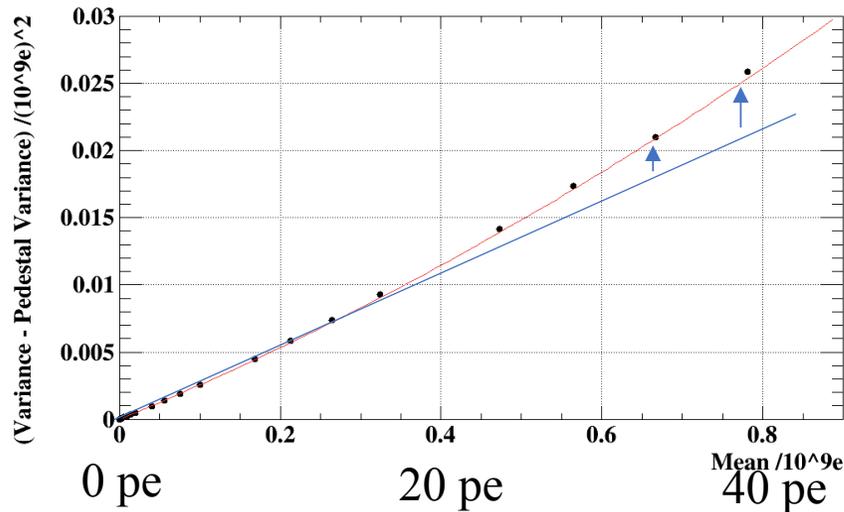
- large ENF when over voltage is large
→ can be explained by correlated noises

Light Intensity

- large ENF when using too weak light
- converge in strong light region
→ dark count contribution in weak light region?

Non-linearity of variance vs mean

variance vs mean @OV=2.2 V

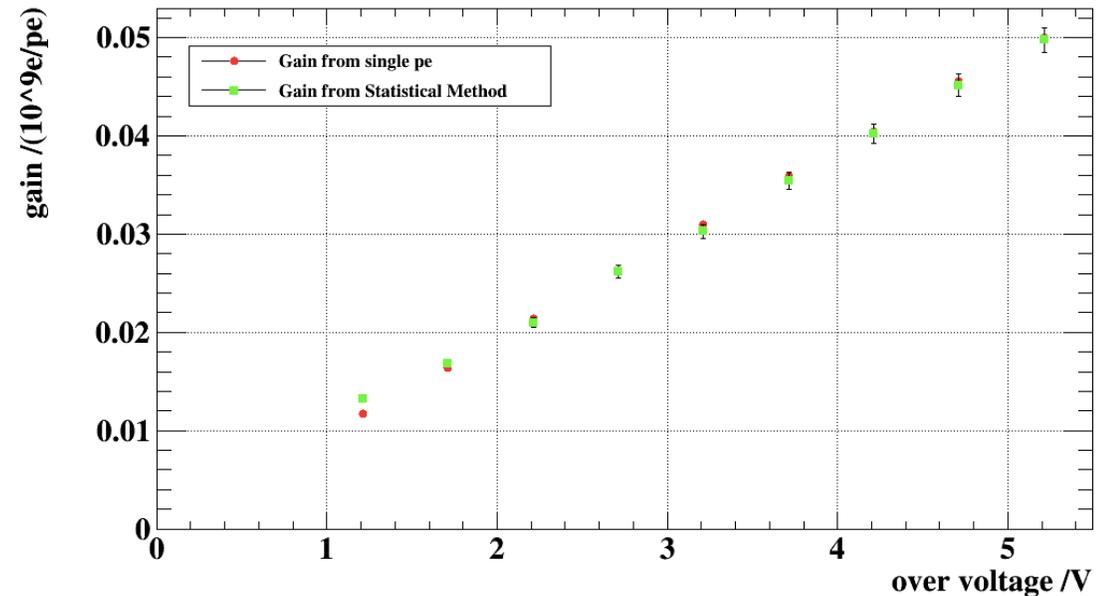


measure at various
over voltage



- Plot of variance vs mean is not linear.
- because of improper assumption?
 - crosstalk/after-pulse probability, delayed crosstalk
 - model of correlated noises
- fit by quadratic and use slope @origin

Gain vs Over Voltage



- ENF was calculated with light whose mean p.e. is ~ 4 .
- precision: $\sim 2.5\%$
- Consistent gain was obtained.

Summary

➤ Summary

- Previous study shows gain can be obtained from statistics of charge distribution.
- We tested the method with Hamamatsu MPPC.
- Although it was found that ENF & variance/mean depend on light intensity, we obtained gain consistent with that from single p.e.

➤ Problems & to do

- The reason of
 - large ENF @weak light
 - non-linearity b/w variance & meanare not understood.
→ investigate using simulation

Outline

- Introduction: About SiPM
- Statistical Method
- Waveform Method

Previous Study

○ When pulses are separated,

- $charge = \int V(t) dt \propto N_{pulse} \cdot gain$
- $height\ squared = \int (V(t))^2 dt \propto N_{pulse} \cdot gain^2$

→ $gain \propto height\ squared / charge$

- You can monitor gain without any dedicated run when waveform is accessible.
- Constant light source is not needed.

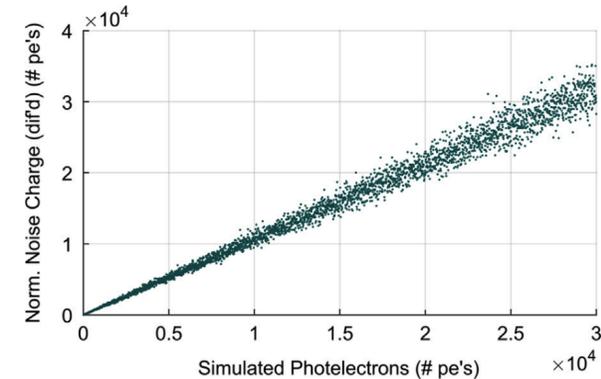
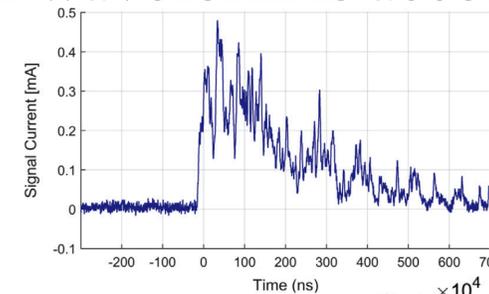
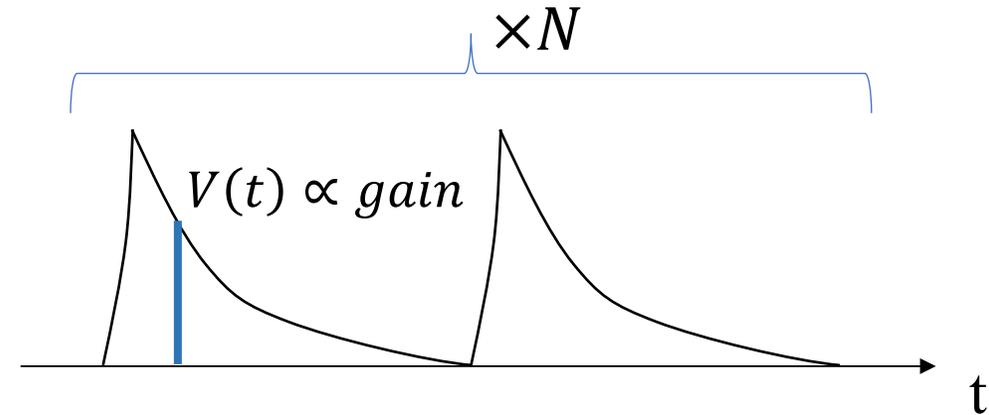
○ to separate pulses, take derivatives

- Considering S/N, 2nd derivative is best.

○ has been demonstrated using PMT (sampling rate: 2.5 GHz)

○ We applied this method to SiPM for the first time.

→ effect of overlapping due to prompt crosstalk



Extension of the model

○ effect of white noise $V_{noise}(t)$

- $charge = \int (V(t) + V_{noise}(t)) dt \propto N_{pulse} \cdot gain$

- $height\ squared = \int (V(t) + V_{noise}(t))^2 dt \simeq const. \cdot N_{pulse} \cdot gain^2 + noise$

→ $height\ squared = c_0 + c_1 \cdot charge, c_1 \propto gain$

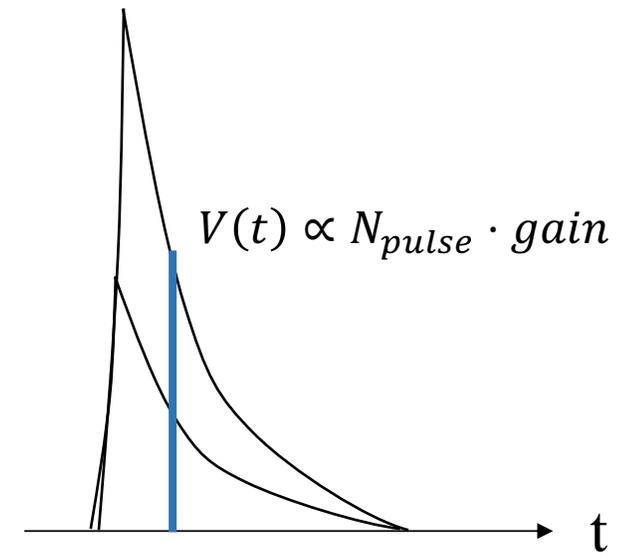
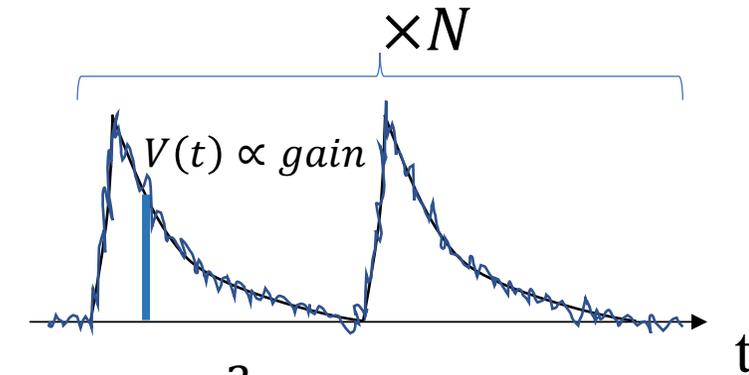
○ effect of overlapping

- due to large # of photoelectrons in unit time
- due to prompt crosstalk

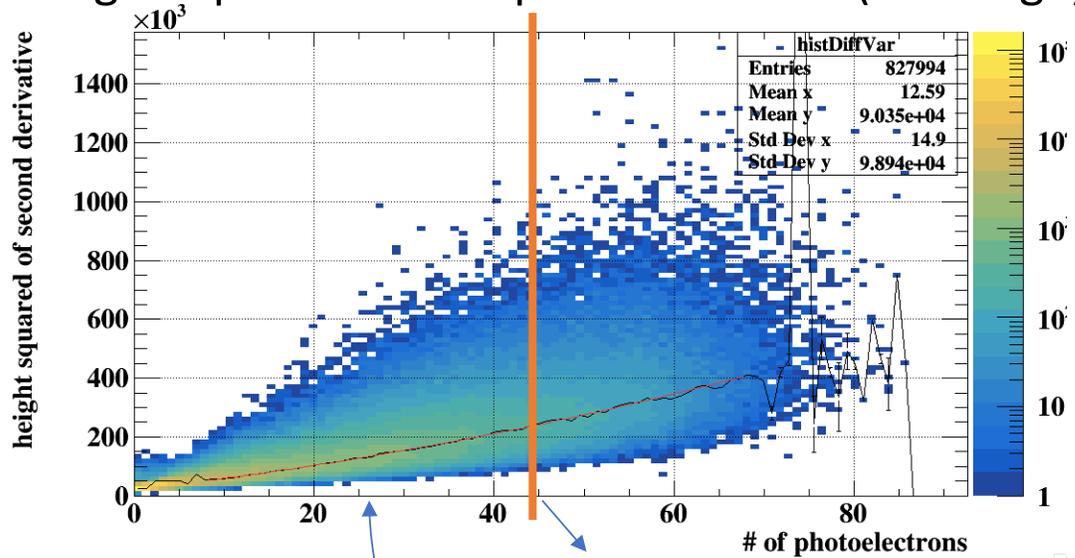
When completely overlapped,

- $height\ squared = \int (V(t))^2 dt \propto N_{pulse}^2 \cdot gain^2$

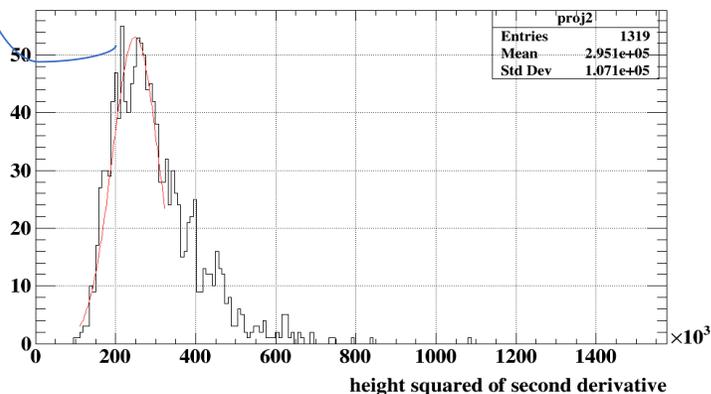
→ Overlapping results in large height squared.



Result

height squared vs # of photoelectrons (\propto Charge)

Height Squared Histogram



peak is drawn as line

○ offset

- effect of white noise

○ tail

- effect of overlap due to crosstalk
- search for peak @ each # of photoelectron

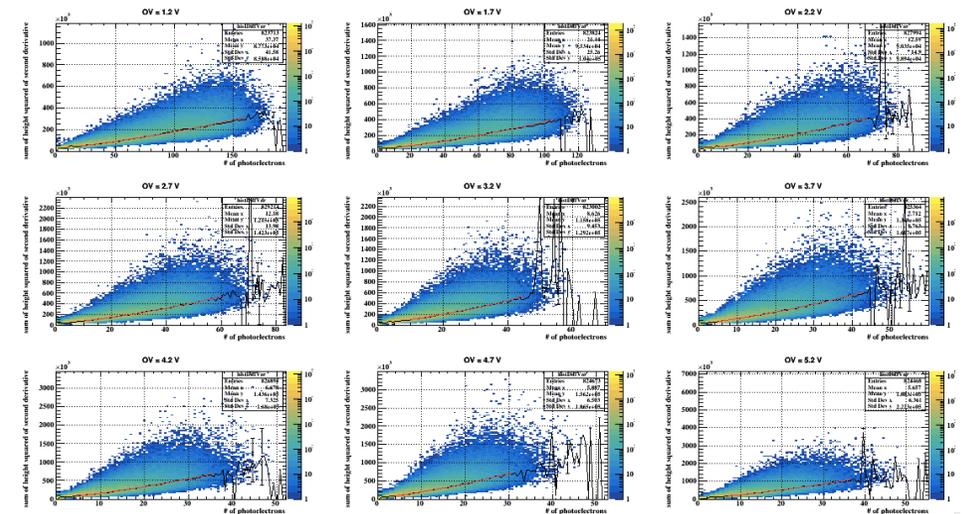
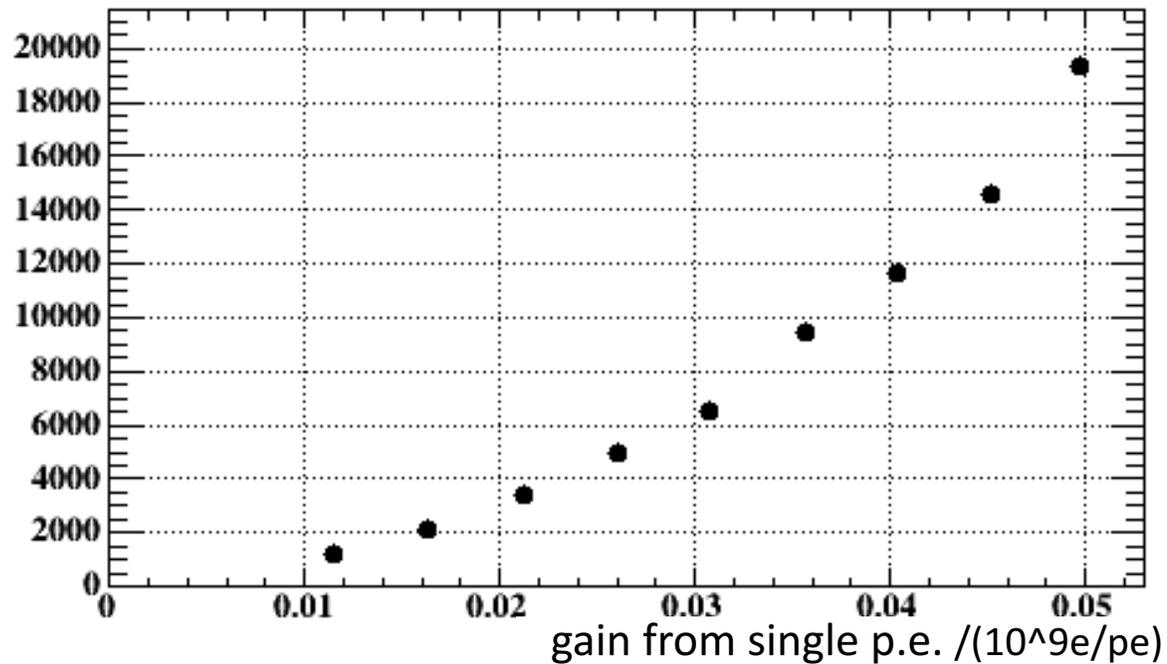
○ peak shift

- deviate from linear in large # of photoelectrons
- Large # of photoelectrons in unit time makes much overlapping.

Result

➤ Measurement changing Over Voltage

slope @origin



- Correlation is not linear, but clear enough to monitor gain.
- If you calibrate beforehand, you can also obtain absolute gain.

Summary

➤ Summary

- Previous study shows PMT gain can be monitored using waveform.
- We considered effect of noise and overlap.
- We obtained correlation clear enough to monitor gain.

➤ Problems & to do

- Stability of correlation must be checked.
 - noise
 - individual difference
- should be checked using other light source such as scintillator
- Effect of sampling rate should be checked.

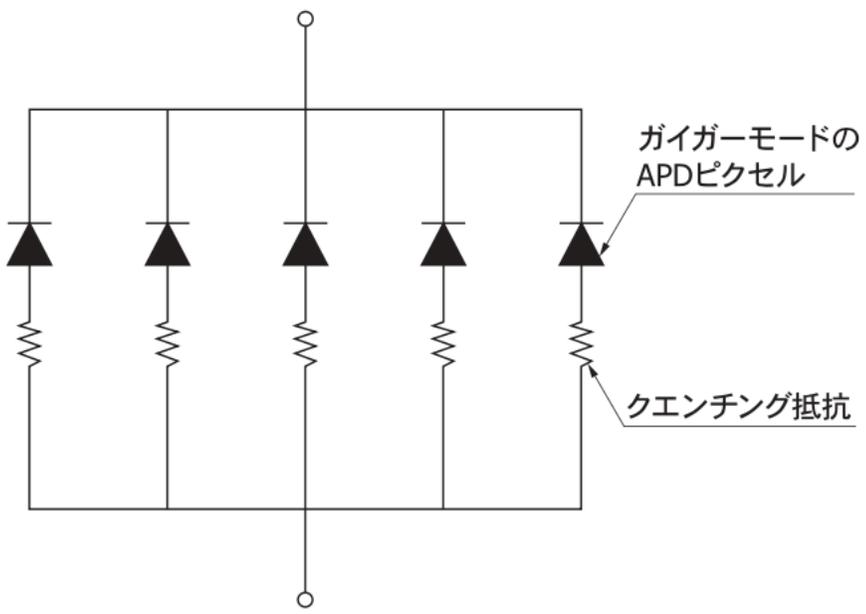
Summary as Comparative Study

- Single p.e.
 - measure single p.e. directly
 - peaks must be separated
- Statistical Method
 - use mean & variance
 - advantage: S/N is not required
 - limitation : need constant light source, assumption on ENF
- Waveform Method
 - use waveform
 - advantage: w/o dedicated run
 - limitation: need calibration to obtain gain itself
- To understand behavior of each variable, simulation study will be continued.

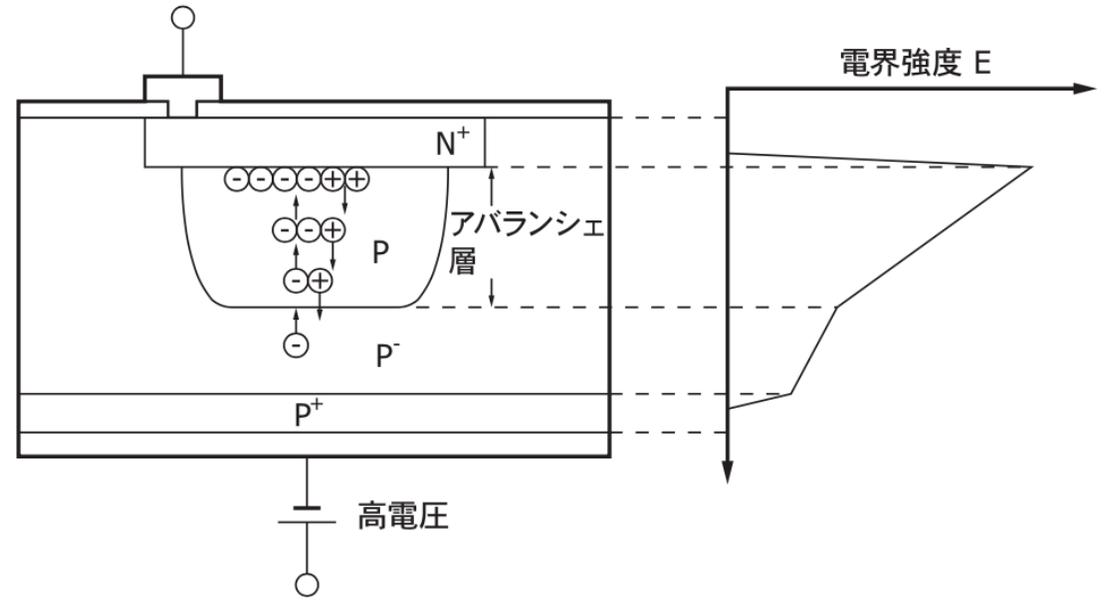


Back up

SiPM



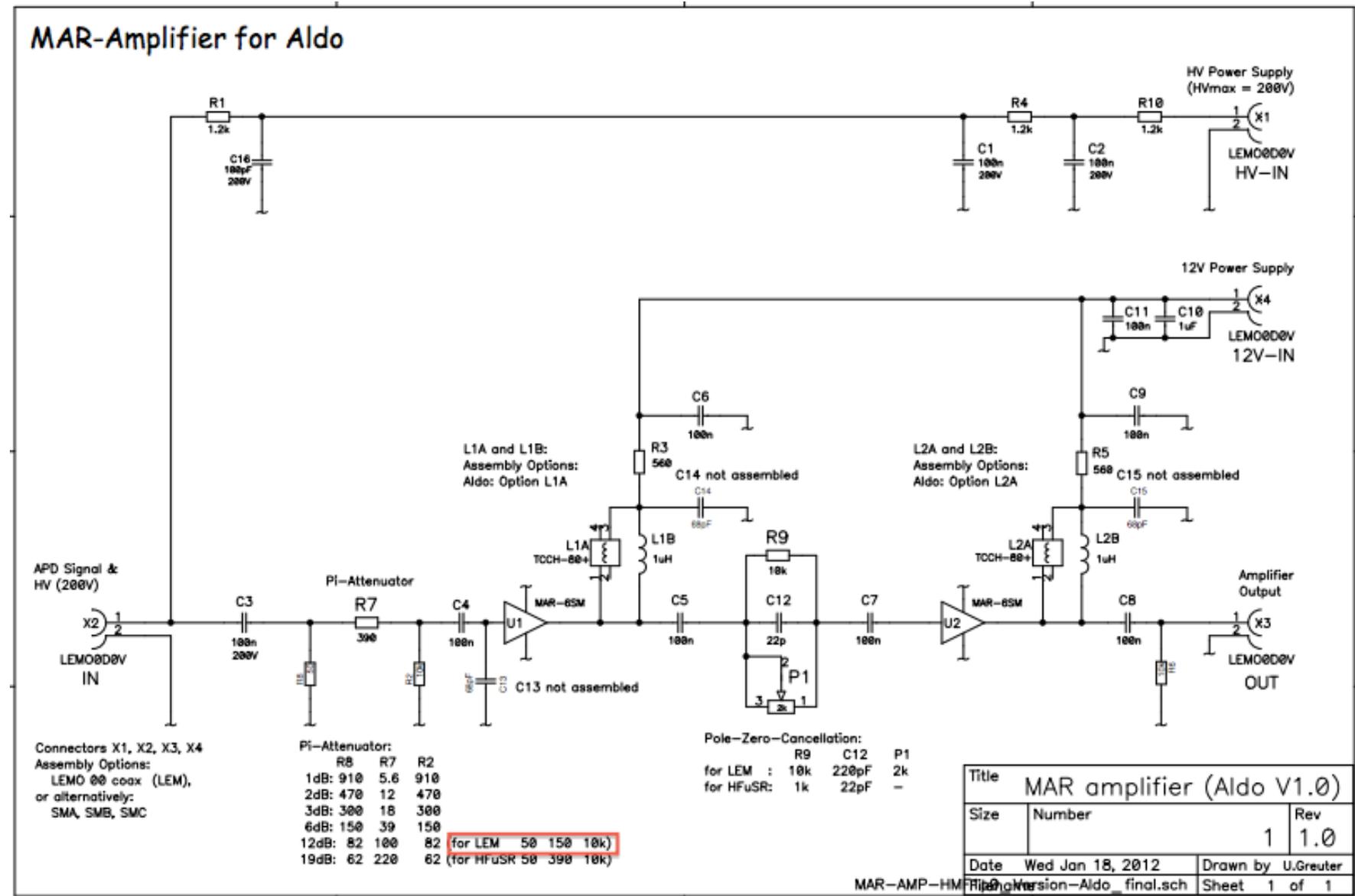
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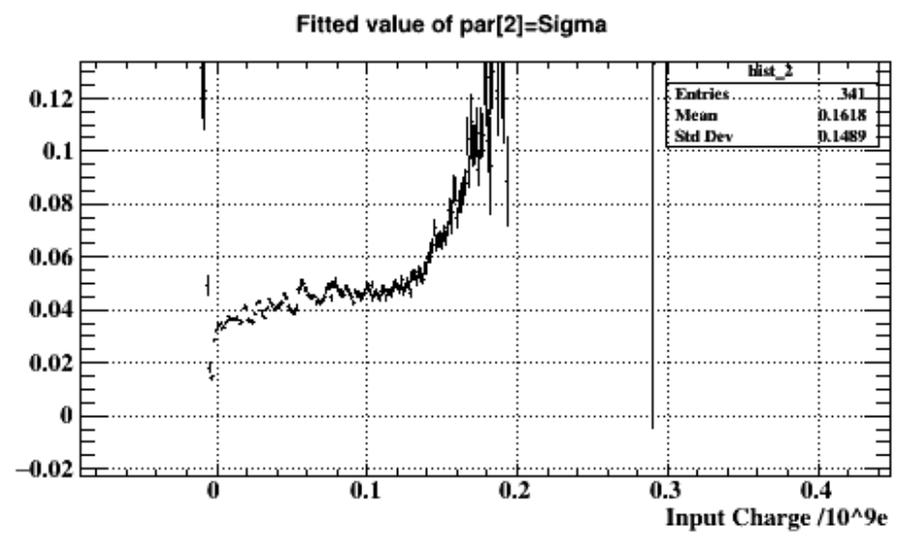
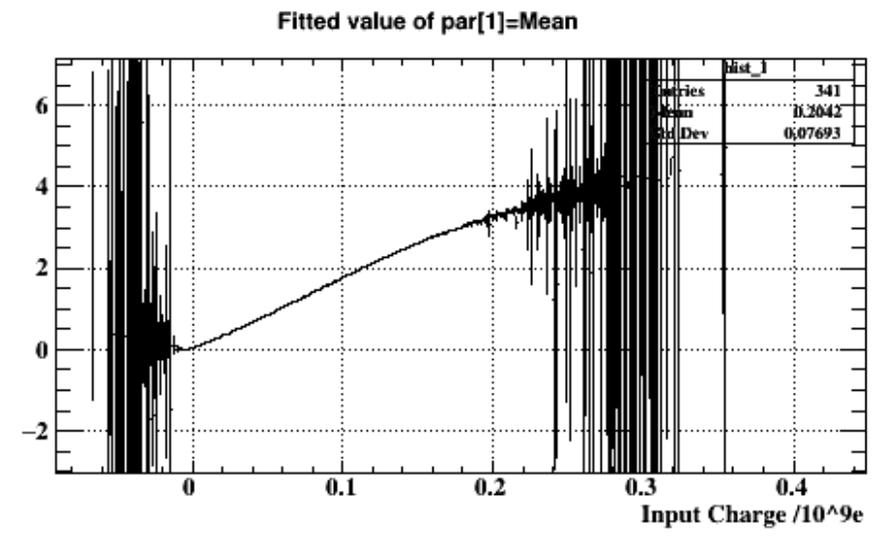
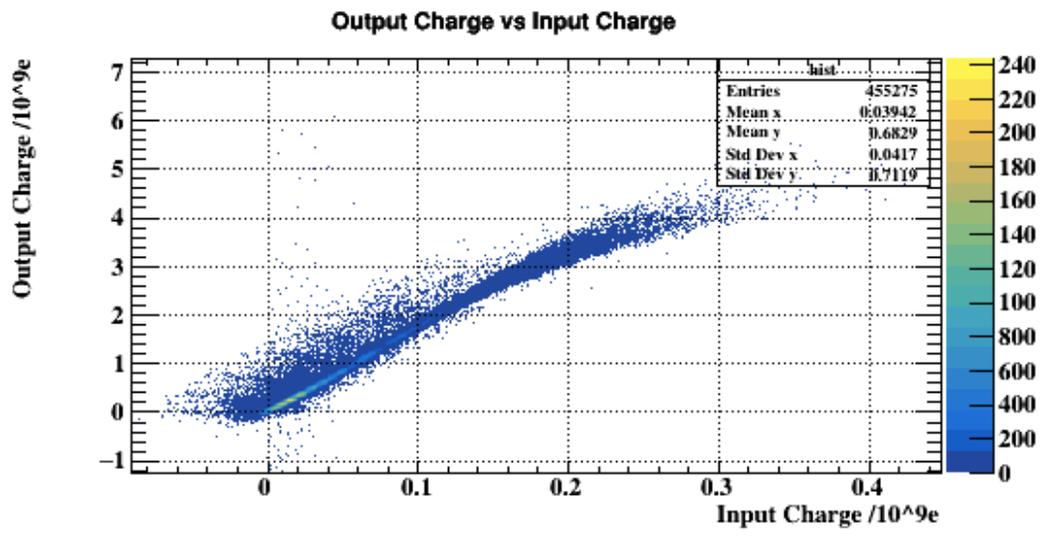
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Hamamatsu 光半導体素子ハンドブック

PSI amp

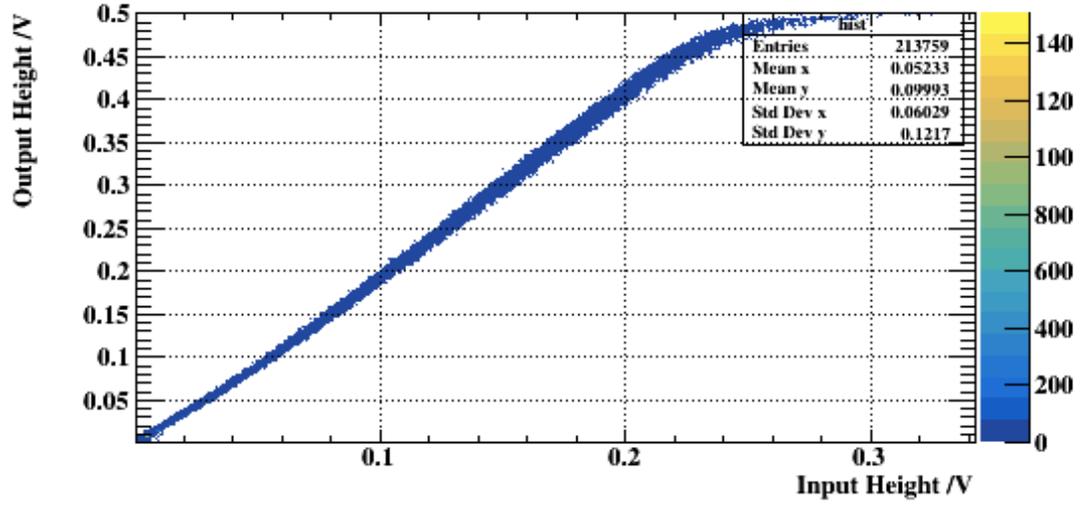


Amp Linearity (Charge)

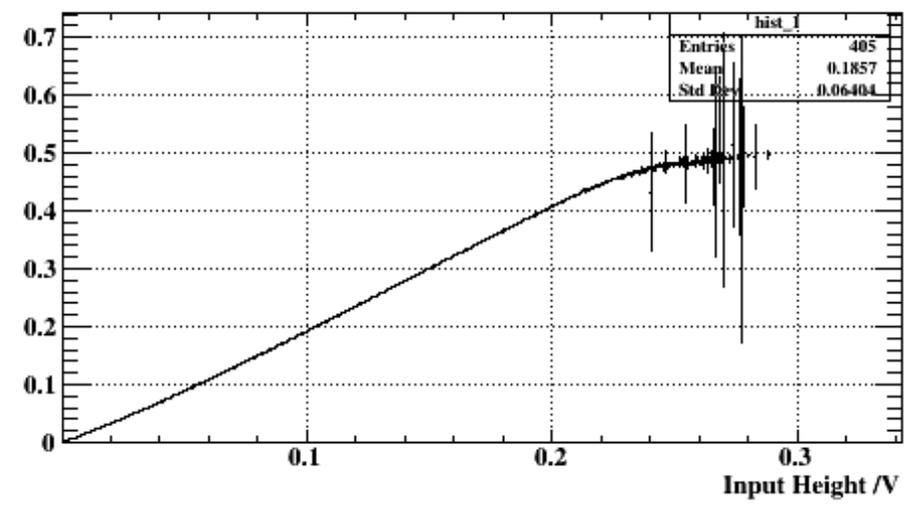


Amp Linearity (Height)

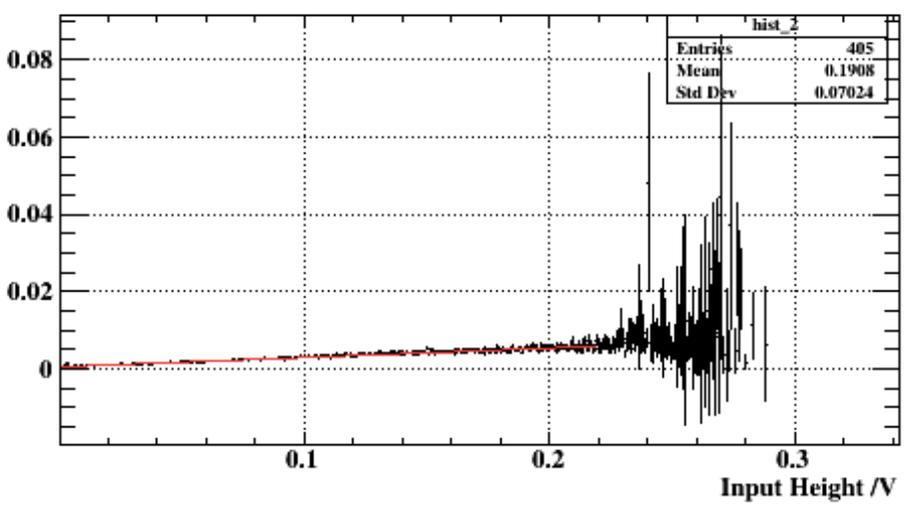
Output Height vs Input Height



Fitted value of par[1]=Mean



Fitted value of par[2]=Sigma



Charge distribution

- Generalized Poisson distribution

$$GP_{k;\mu,\lambda} = \frac{\mu(\mu+k\lambda)^{k-1} e^{-(\mu+k\lambda)}}{k!}$$

- $mean = \frac{\mu}{1-\lambda}$
- $variance = \frac{\mu}{(1-\lambda)^3}$

- broaden following Gaussian distribution

$$Gauss_{x;k,\sigma_k} = \frac{1}{\sqrt{2\pi}\sigma_k} \exp\left(-\frac{(x-x_k)^2}{2\sigma_k^2}\right)$$

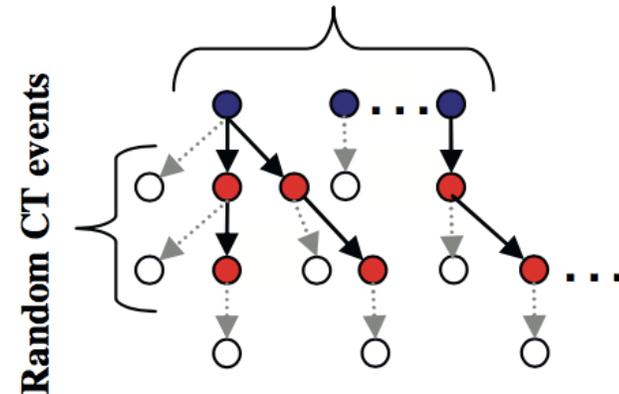
- charge of k electron: $x_k = pedestal + gain \cdot k$
- standard deviation of kth peak: $\sigma_k^2 = \sigma_0^2 + \sigma_c^2 \cdot k$

- Convolution

$$\frac{dp}{dx} = \sum_{k=0} GP_{k;\mu,\lambda} \cdot Gauss_{x;k,\sigma_k}$$

- $mean - pedestal = \frac{\mu}{1-\lambda} gain$
- $var - \sigma_0^2 = \left(\frac{gain}{(1-\lambda)^2} + \frac{\sigma_1^2}{gain}\right) (mean - pedestal) \sim \frac{gain}{(1-\lambda)^2} (mean - pedestal)$

Random primary (Photo) events



Dark Count, Delayed Crosstalk, Afterpulsing

○ Dark Count

- DCR (Dark Count Rate): # of Dark Count in a unit time

- $$p_{DC} = \frac{1}{DCR \cdot IntegrationTime}$$

- $$\frac{dp}{dx} = (1 - p_{DC})GP_0; \mu, \lambda$$

$$+ \sum_{k=1} \{ (1 - p_{DC})GP_{k;\mu,\lambda} \cdot Gauss_{x;k,\sigma_k} + p_{DC}GP_{k-1;\mu,\lambda} \cdot Gauss_{x;k-1,\sigma_{k-1}} \}$$

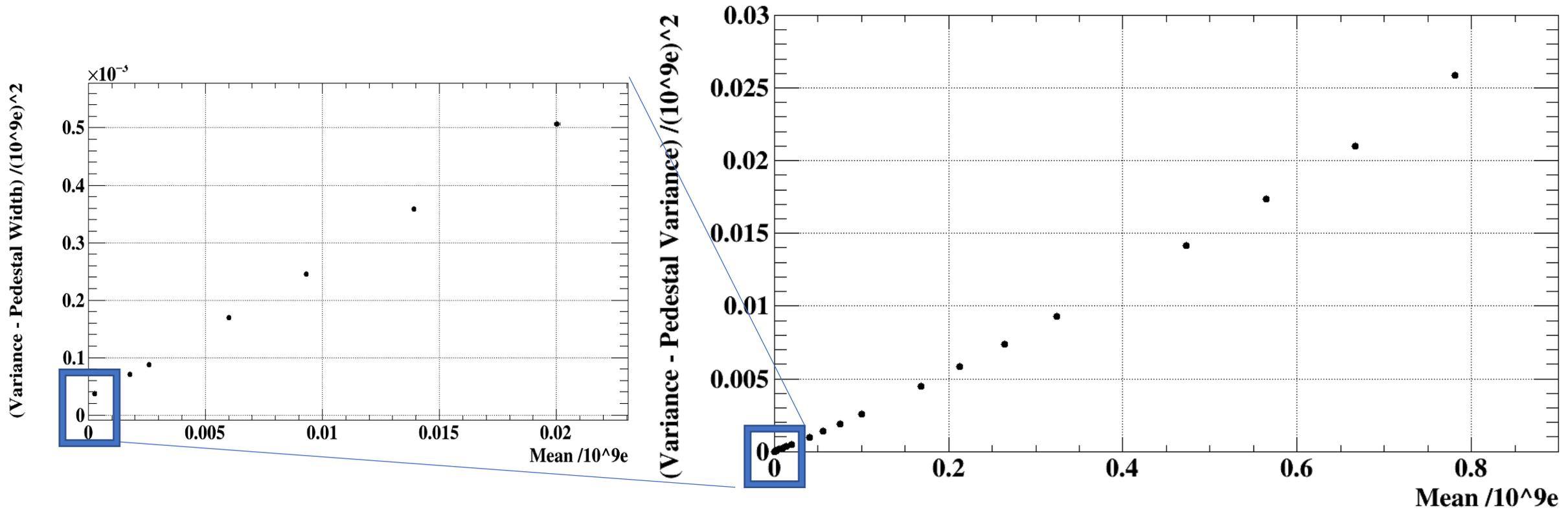
○ Delayed Crosstalk

- sometimes come in integration range
- Charge is same as prompt Crosstalk

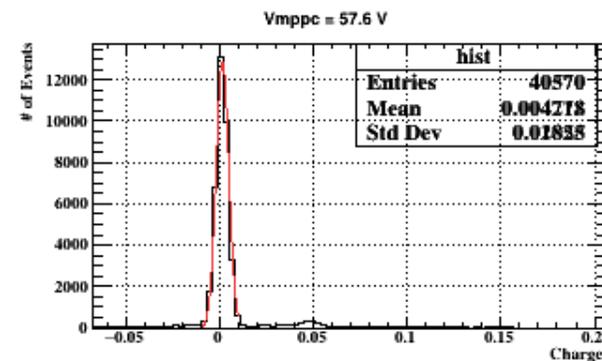
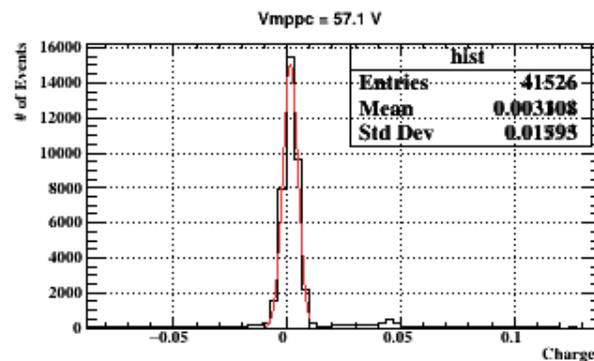
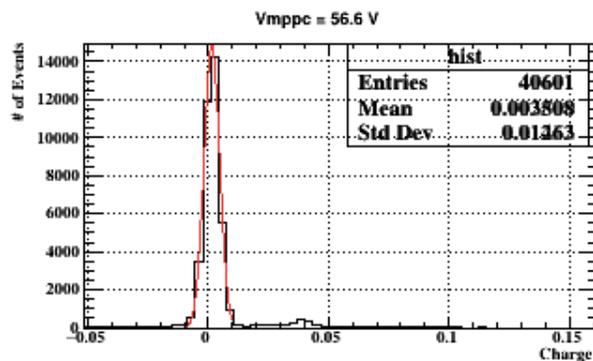
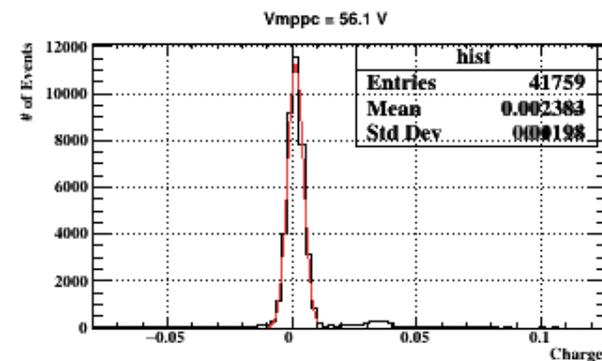
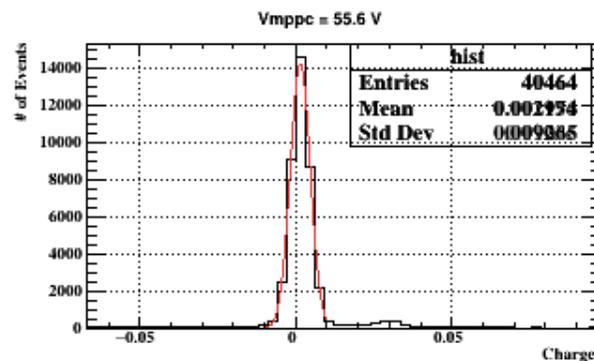
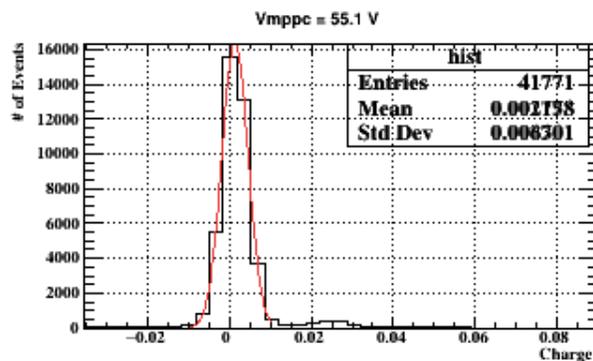
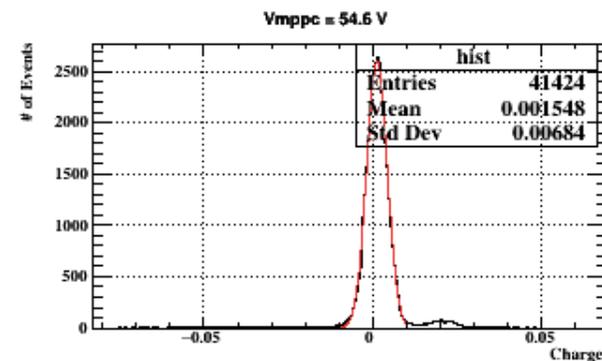
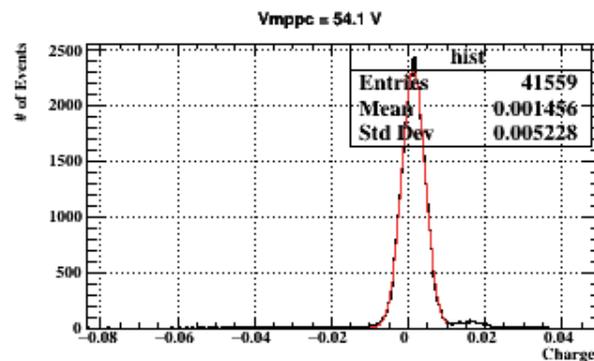
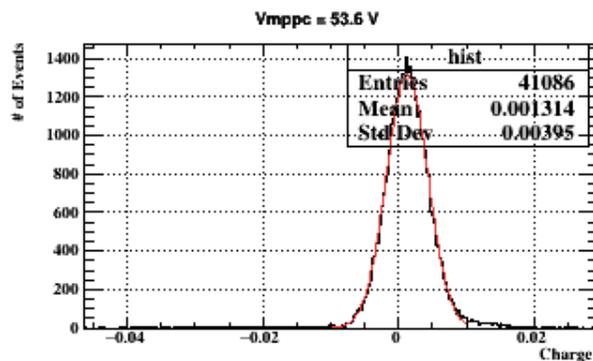
○ AfterPulsing

- amplitude is small because under quenching recovery
- timing follows exponential distribution

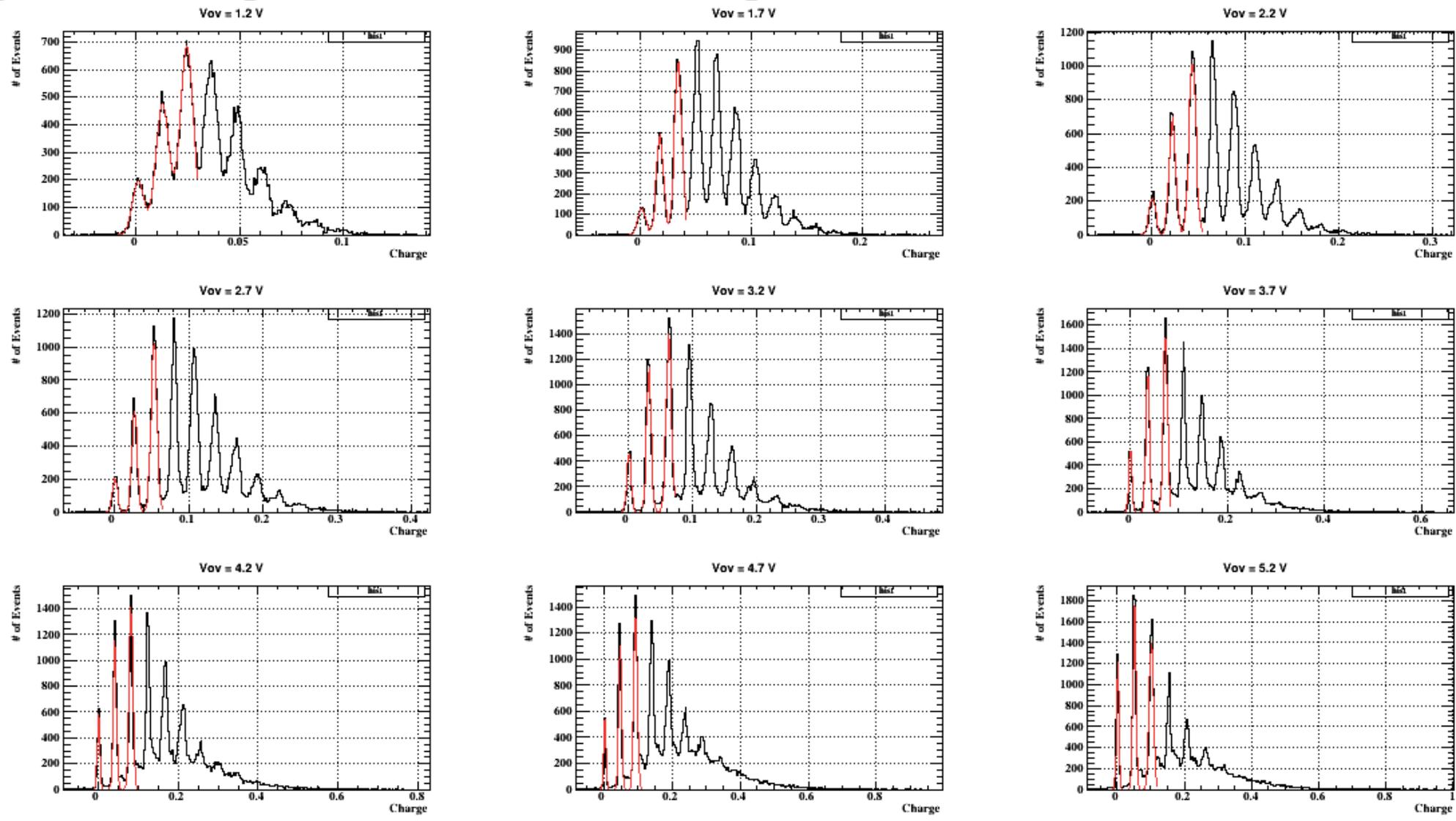
Dark Count



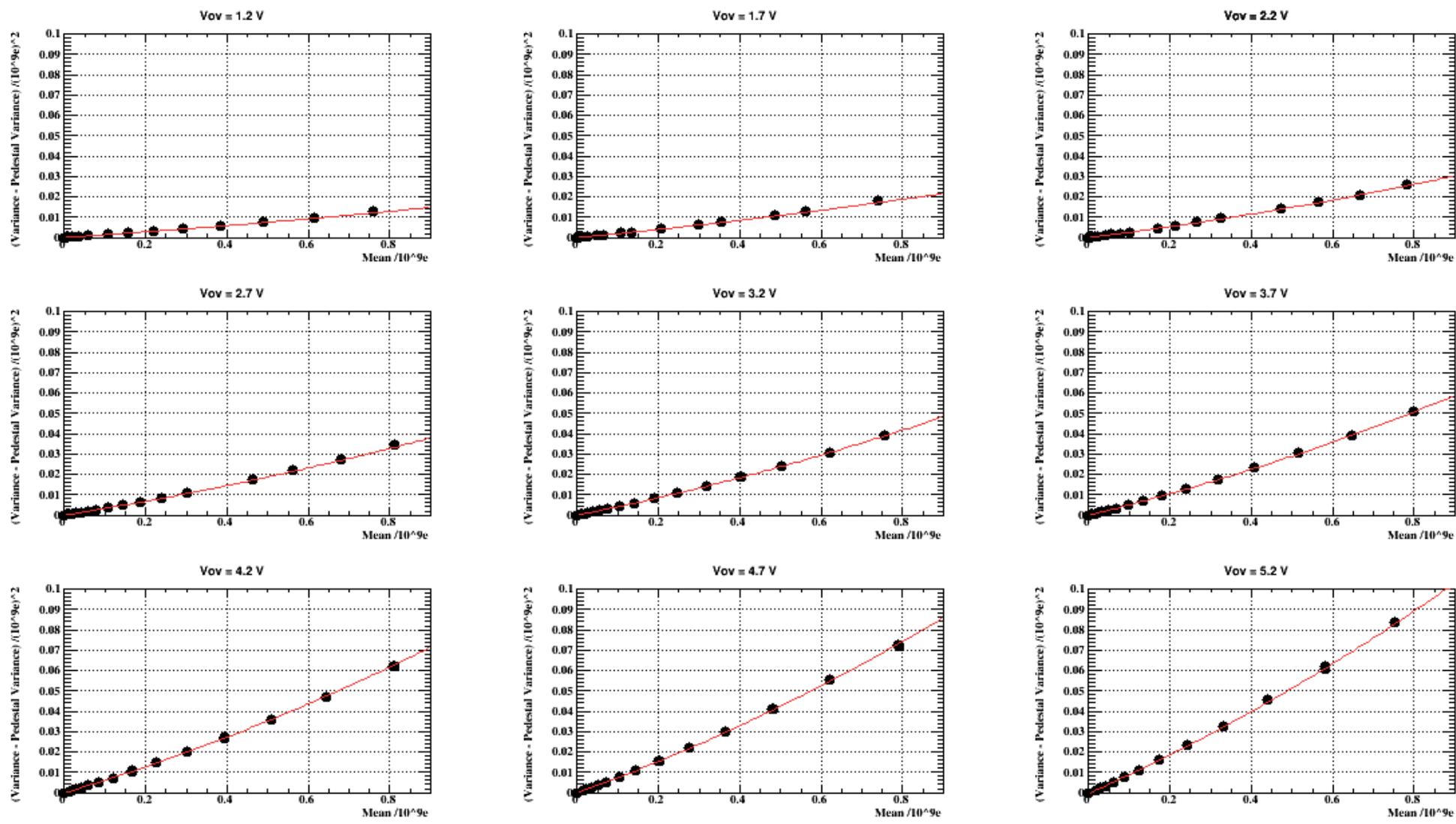
Pedestal Run



Charge Histogram of Weak Light



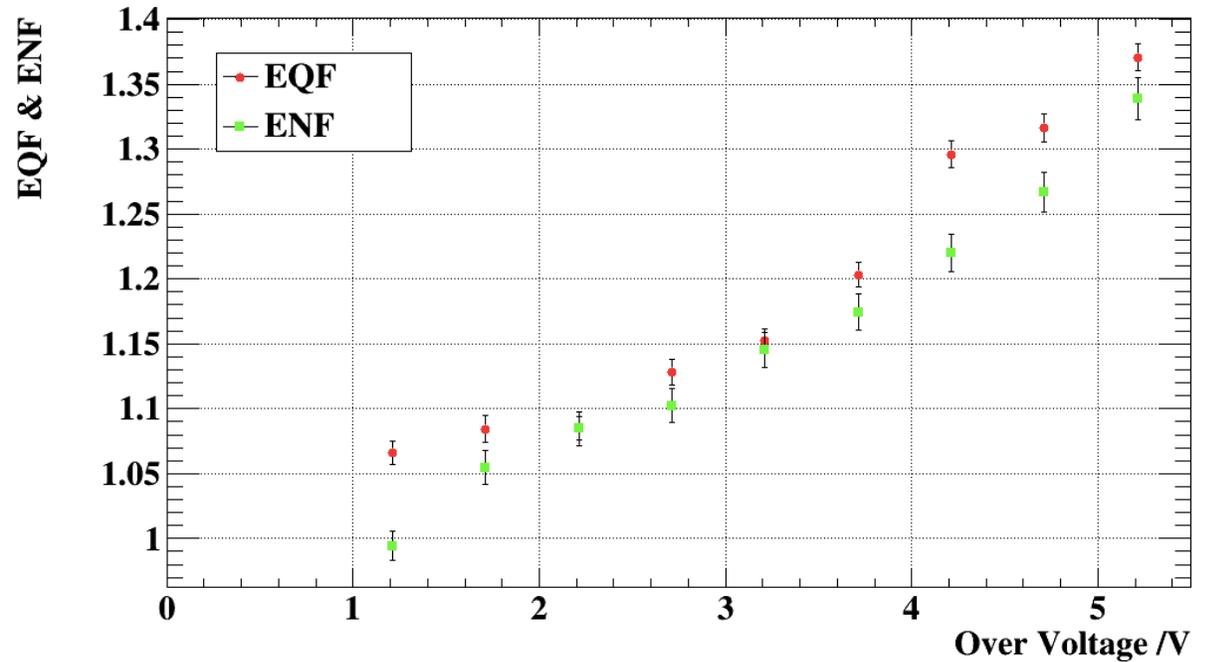
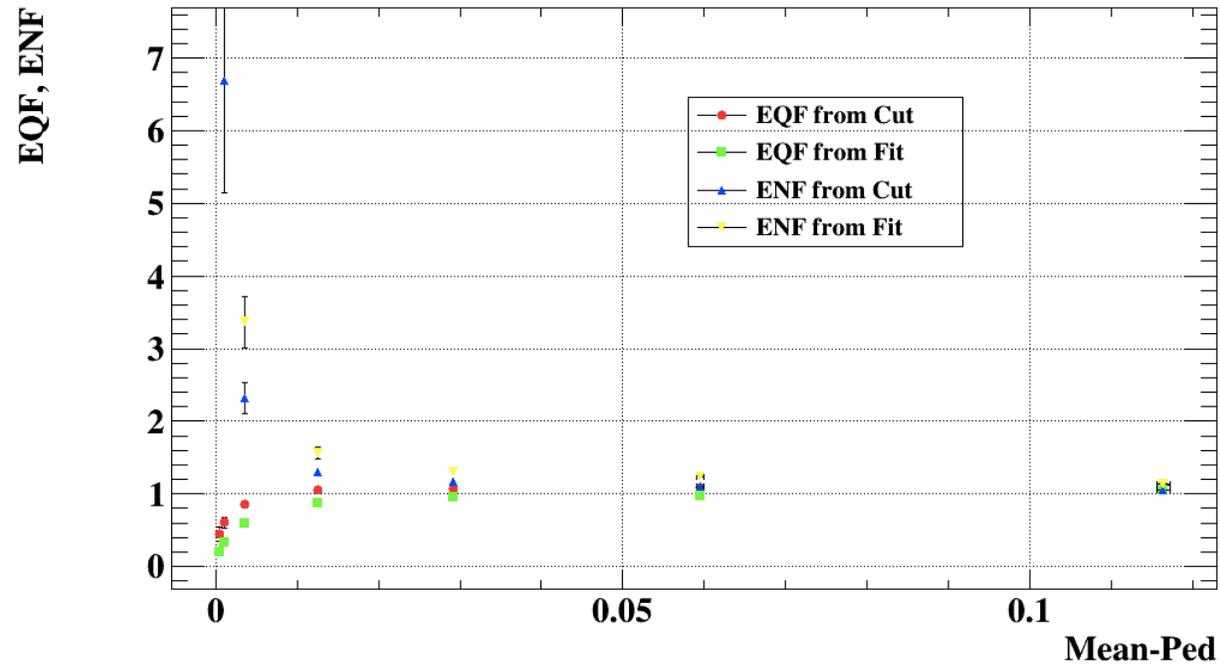
Variance vs Mean



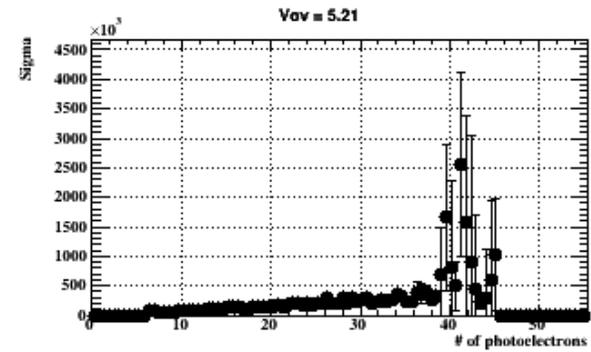
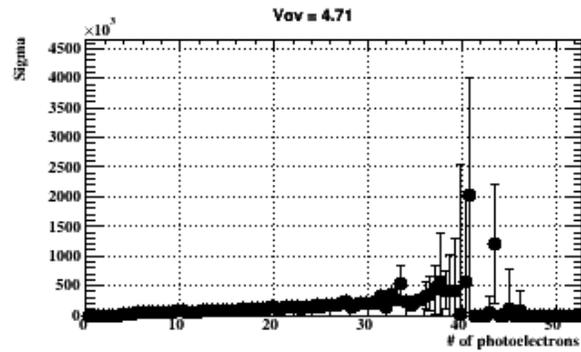
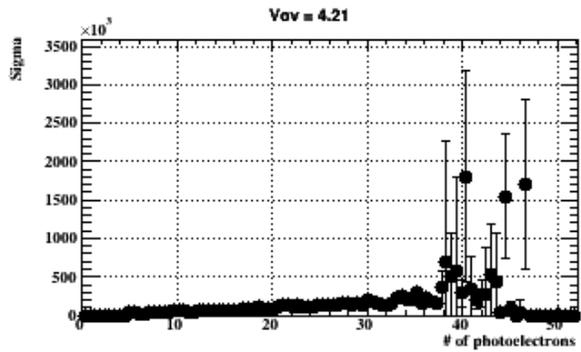
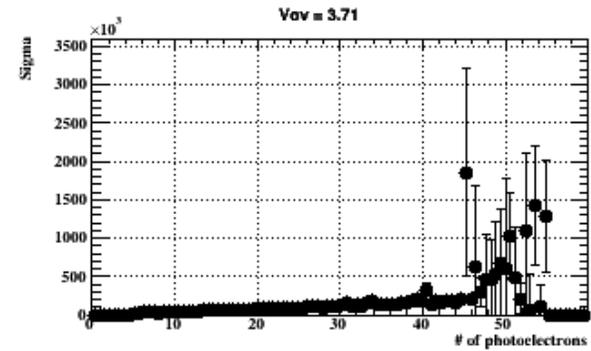
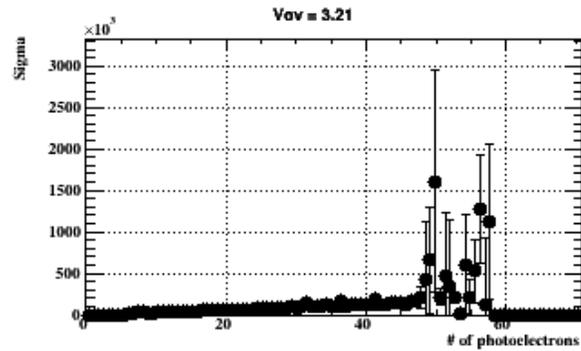
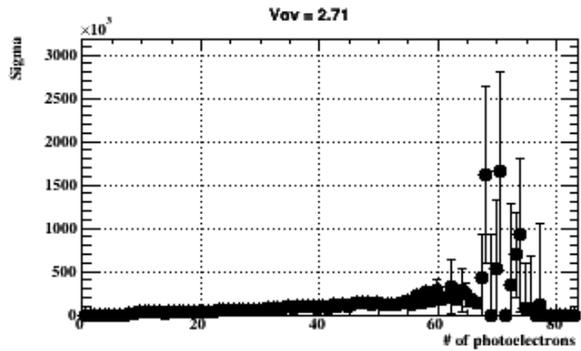
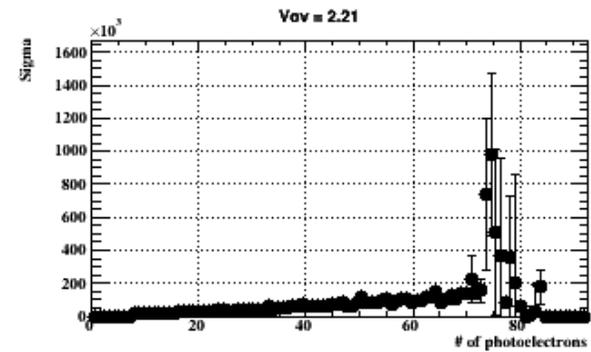
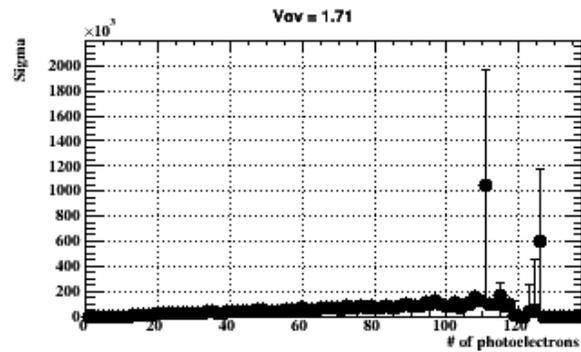
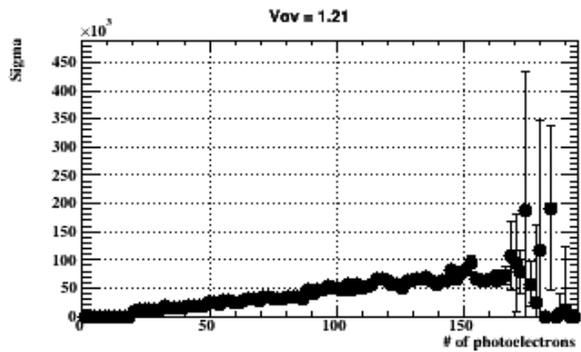
EQF & ENF

- $ENF := \mu \frac{\text{variance} - \sigma_0^2}{(\text{mean} - \text{pedestal})^2}$
- $EQF := \frac{(\text{mean} - \text{pedestal}) / \text{gain}}{\mu}$

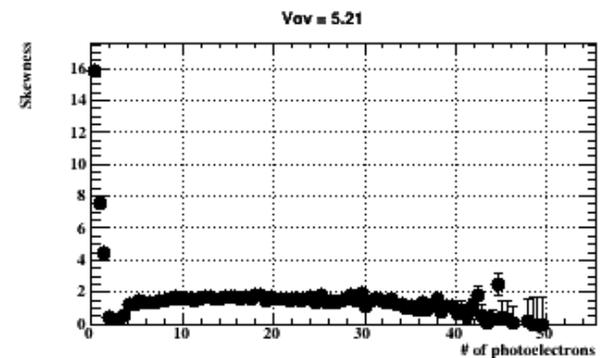
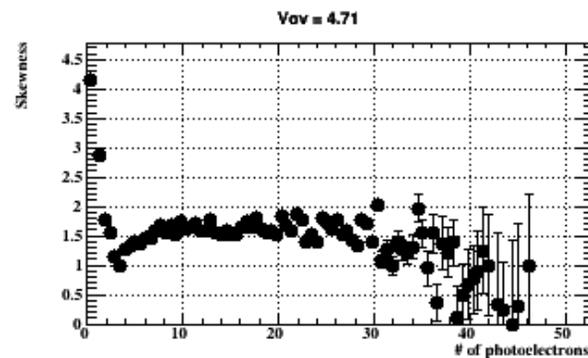
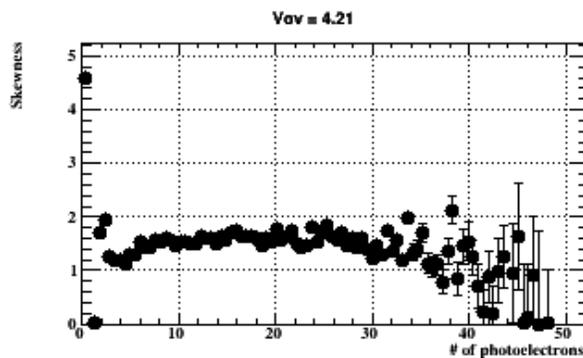
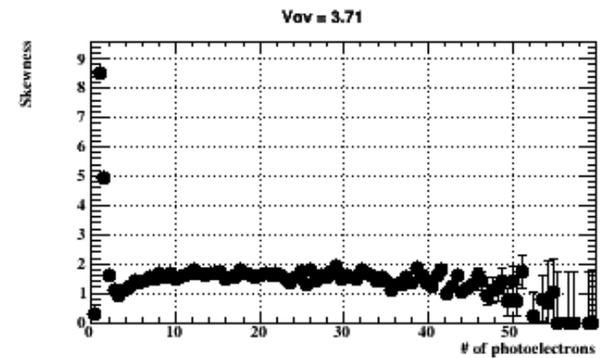
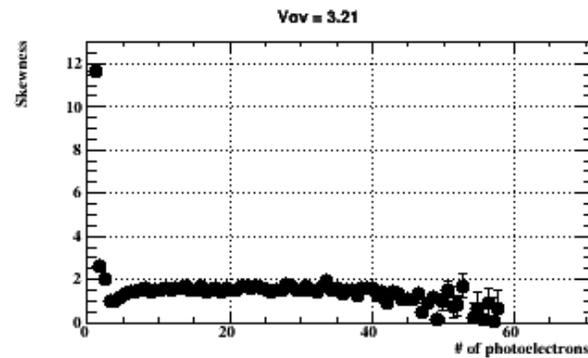
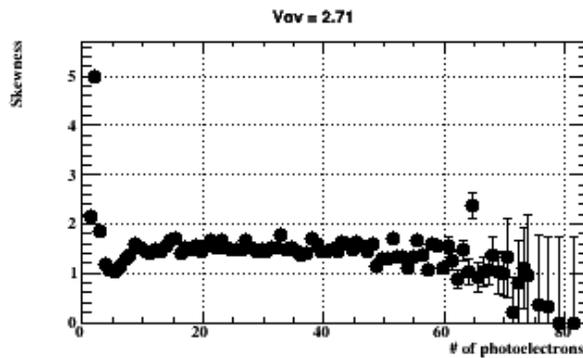
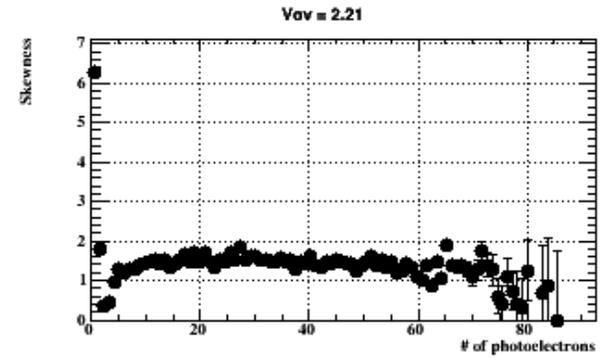
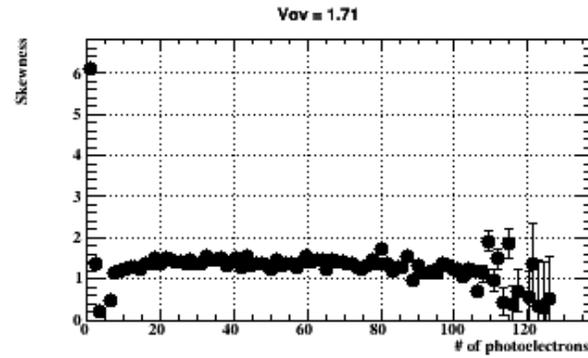
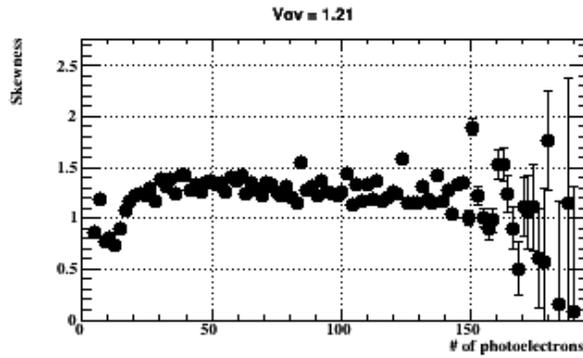
EQF, ENF



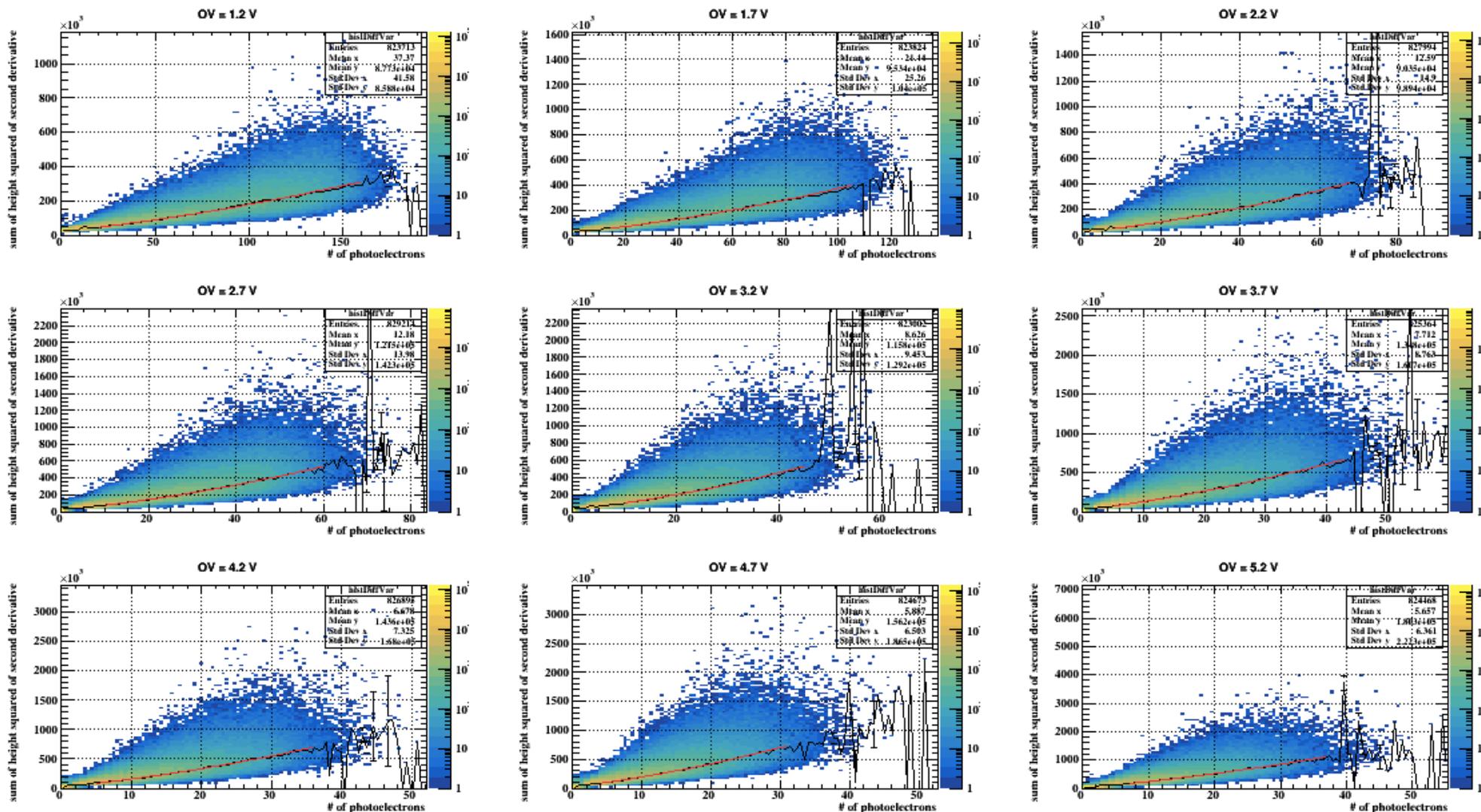
Sigma



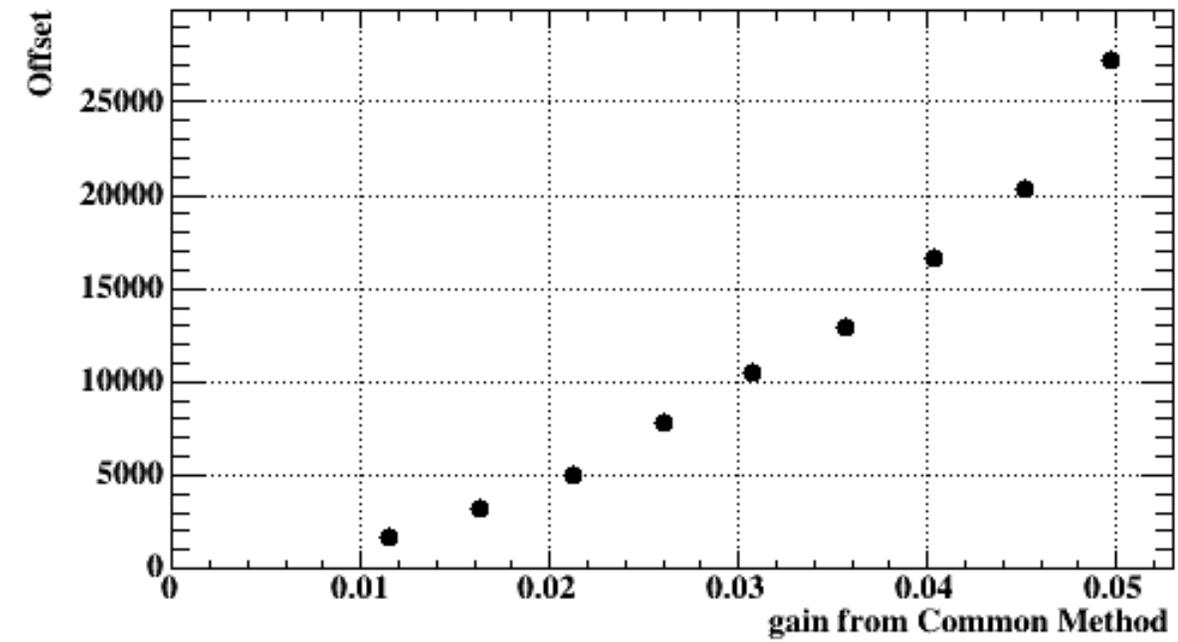
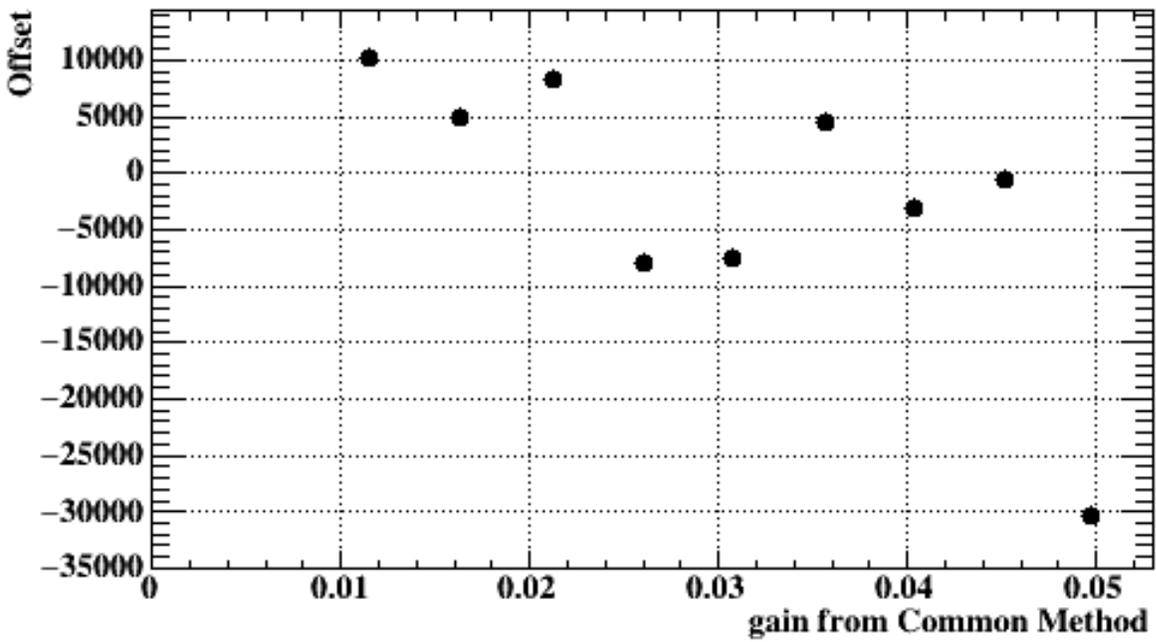
Skewness



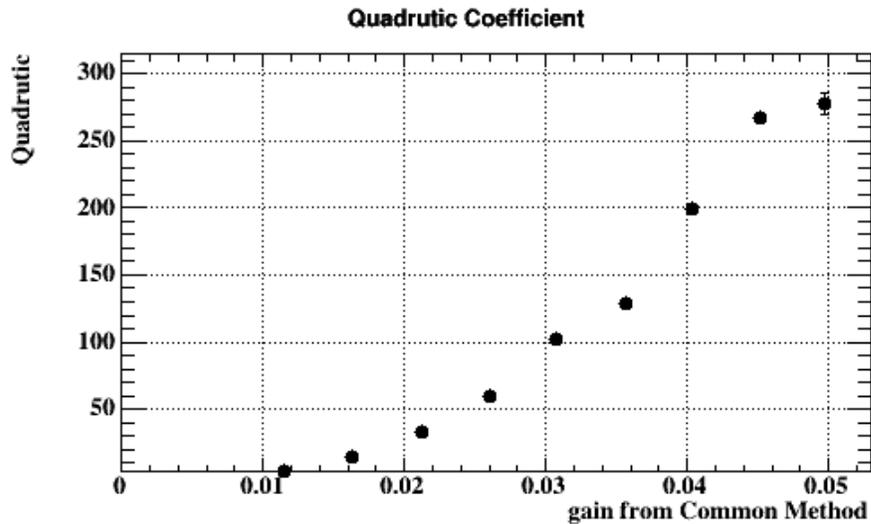
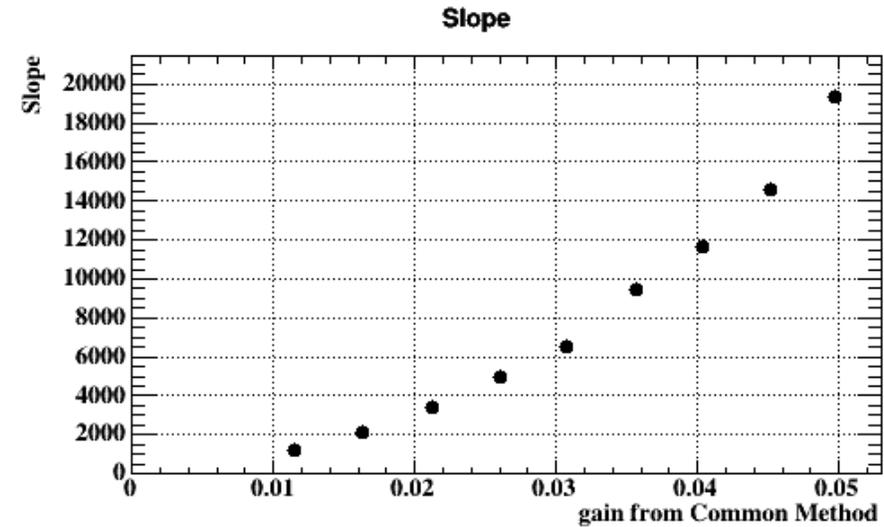
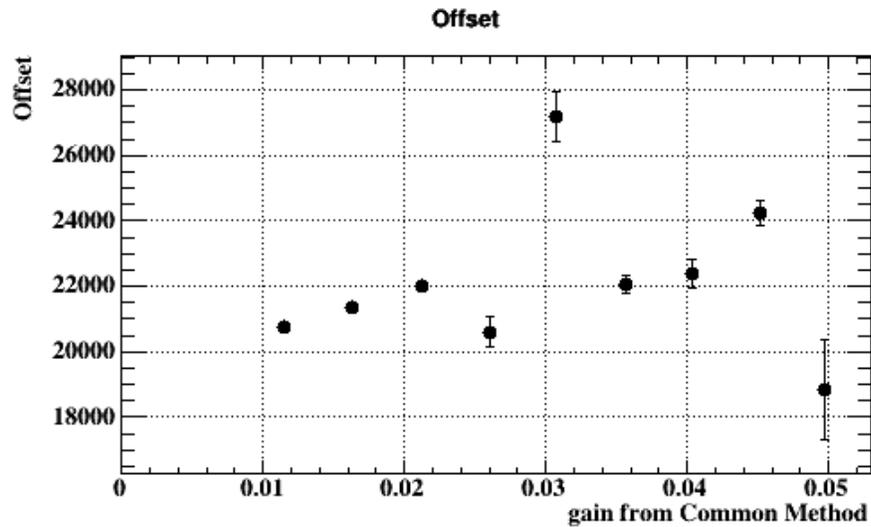
Height Squared vs Charge



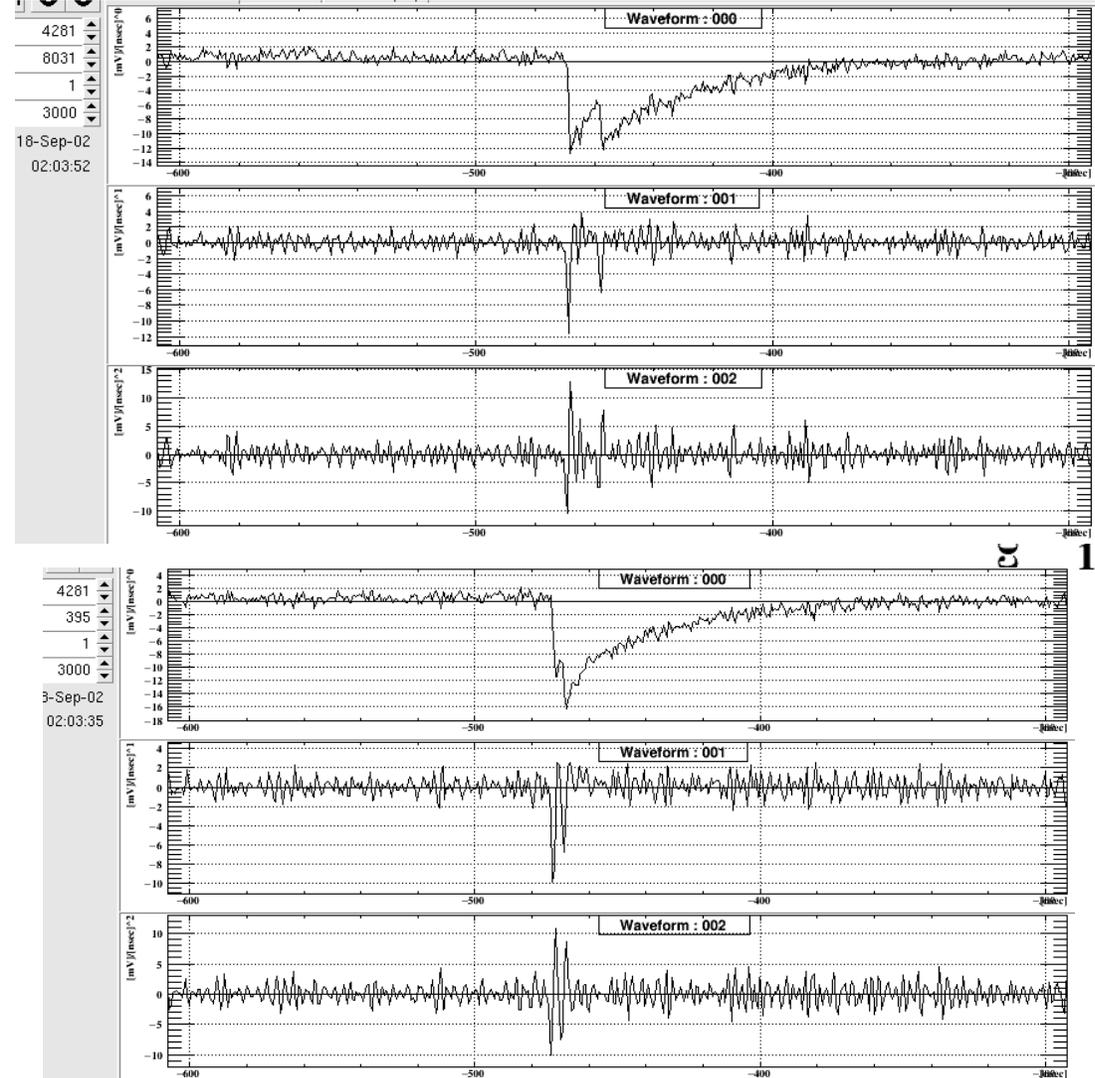
Linear Fitting



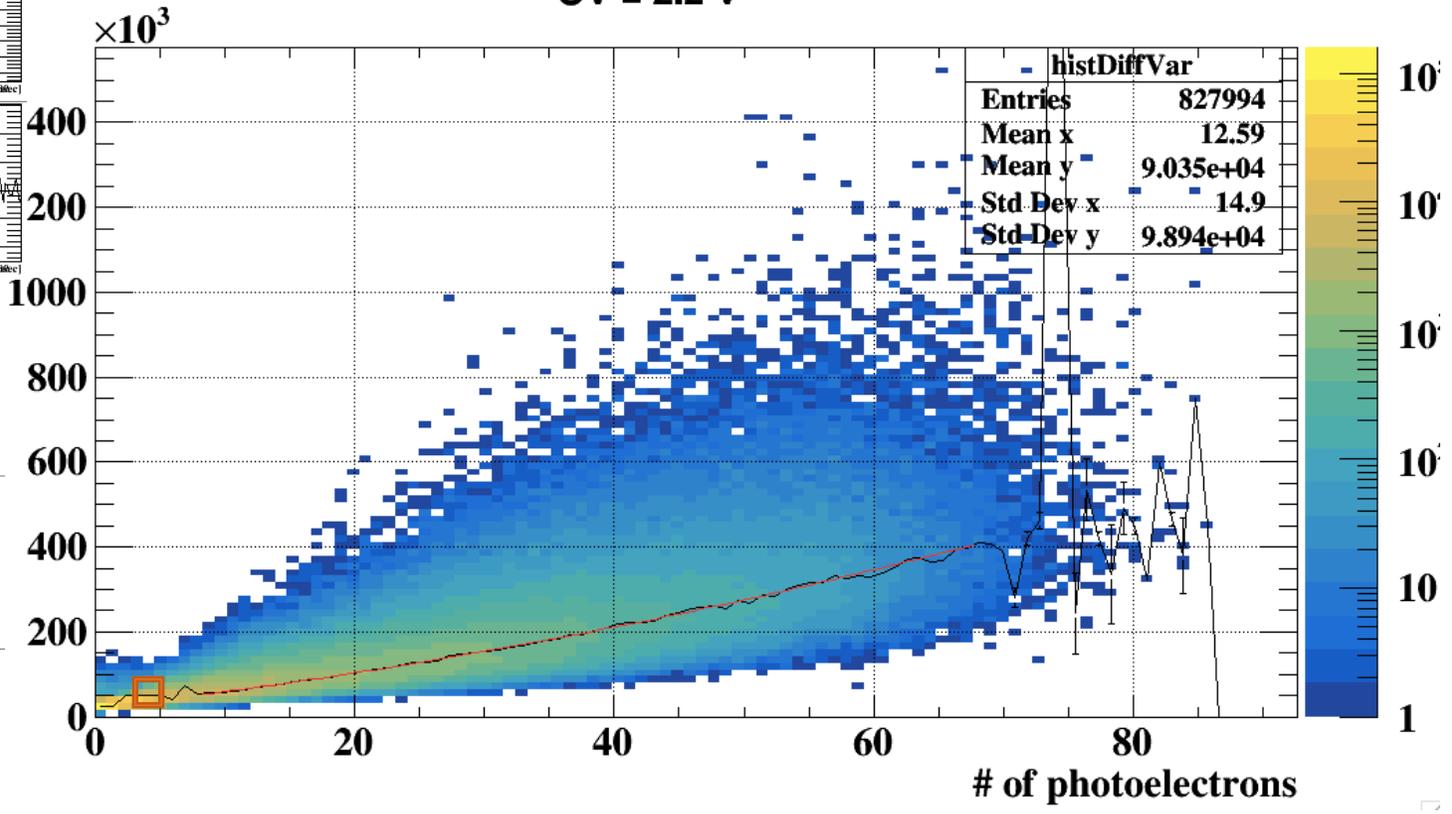
Quadratic Fitting



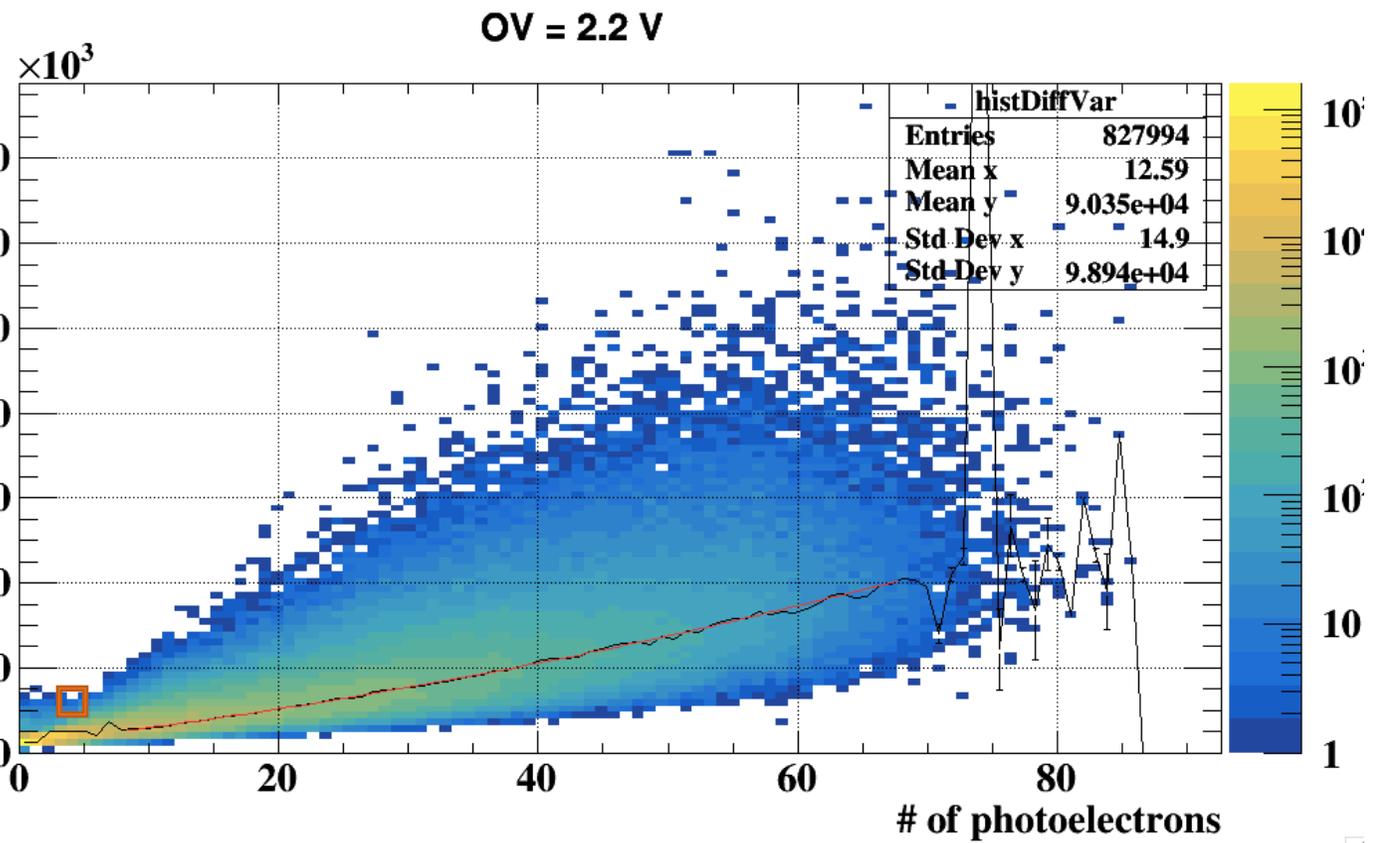
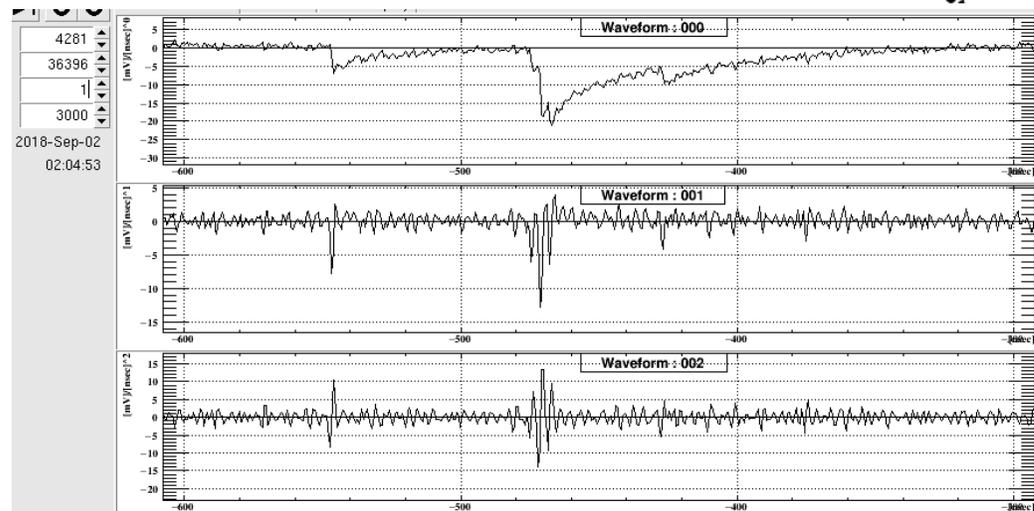
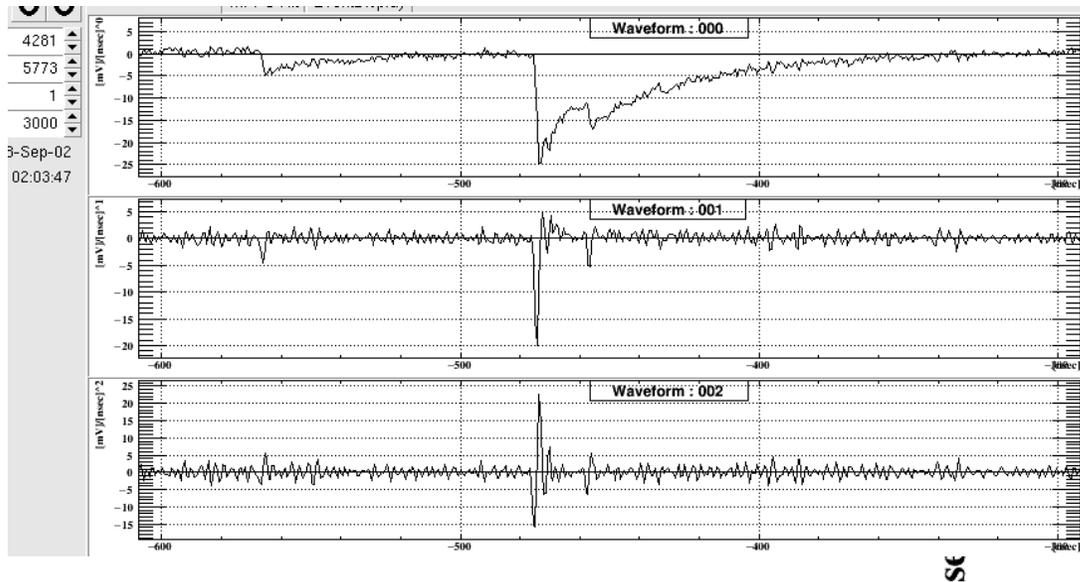
Waveforms



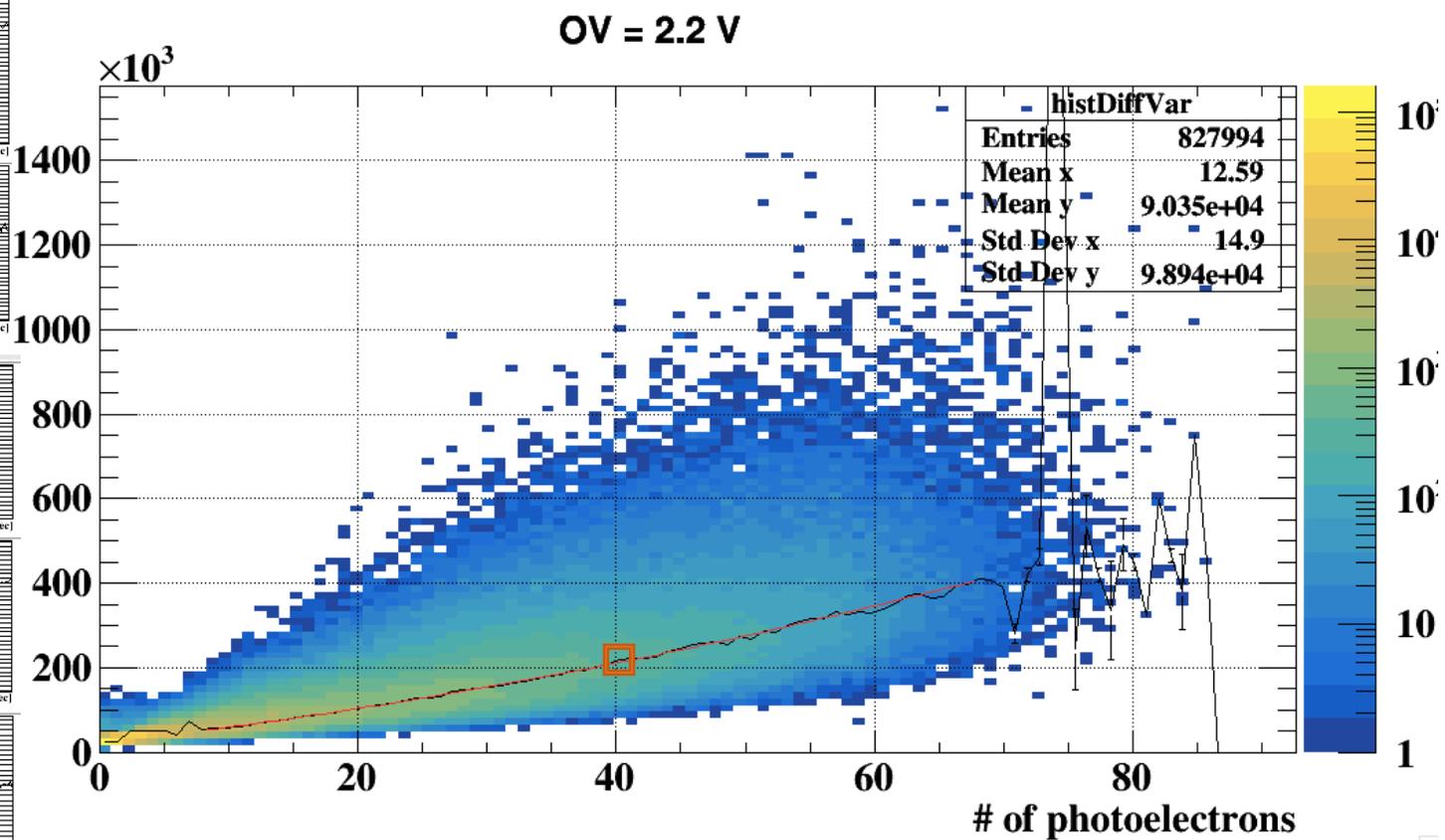
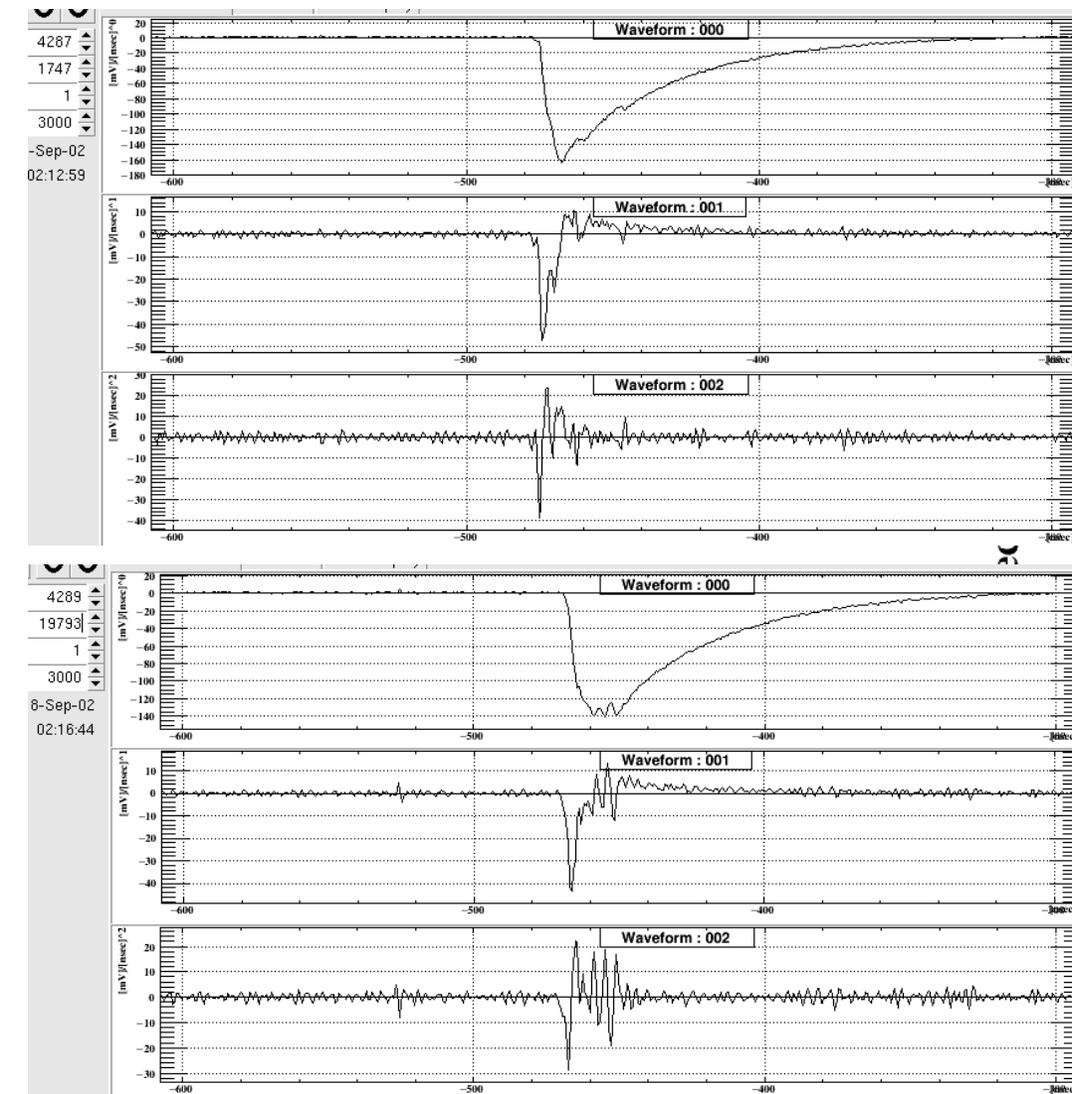
OV = 2.2 V



Waveforms



Waveforms



Waveforms

